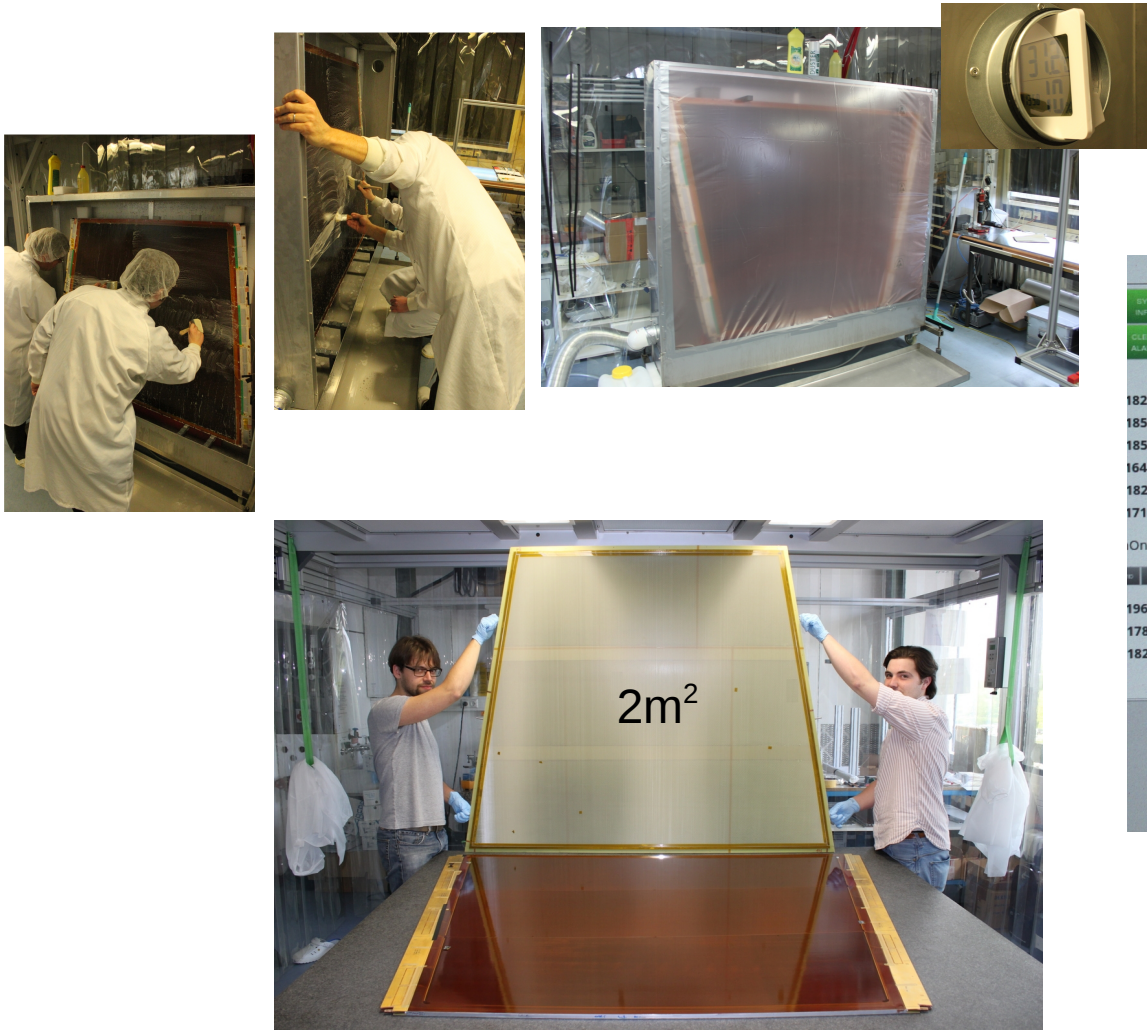


HV Stability of Large Size Resistive Strip Micromegas Chambers



<div>EYE</div> <div>INFO</div> <div>CLEAR</div> <div>ALARM</div>	07.007	hori_4.2	0.500 uA	500.0 V	0.000 uA	0.0 V	Off	
	07.008	hori_4.3	0.500 uA	500.0 V	0.000 uA	0.0 V	Off	
	07.009	hori_4.4	0.500 uA	500.0 V	0.000 uA	0.0 V	Off	
	07.010	hori_4.5	0.500 uA	590.0 V	0.000 uA	0.0 V	Off	
	07.011	hori_4.6	0.500 uA	590.0 V	0.000 uA	0.0 V	Off	
1823	09.000	1.1	2.000 uA	980.0 V	0.016 uA	979.5 V	On	
1859	09.001	1.2	2.000 uA	990.0 V	0.000 uA	989.5 V	On	
1859	09.002	1.3	2.000 uA	1000.0 V	0.010 uA	999.5 V	On	
1644	09.003	1.4	2.000 uA	1.5 V	0.054 uA	0.8 V	On	
1823	09.004	1.5	2.000 uA	1000.0 V	0.000 uA	999.5 V	On	
1716	09.005	1.6	2.000 uA	1000.0 V	0.002 uA	999.8 V	On	
One	09.006	2.1	2.000 uA	990.0 V	0.000 uA	989.5 V	On	
<div>+</div> <div>-</div>	09.007	2.2	2.000 uA	1.5 V	0.044 uA	1.0 V	On	
1966	09.008	2.3	2.000 uA	1000.0 V	0.002 uA	999.5 V	On	
1788	09.009	2.4	2.000 uA	965.0 V	0.004 uA	964.5 V	On	
1823	09.010	2.5	2.000 uA	1000.0 V	0.000 uA	999.5 V	On	
	09.011	2.6	2.000 uA	1000.0 V	0.000 uA	999.8 V	On	
	11.000	3.1	2.000 uA	560.0 V	0.000 uA	0.0 V	Off	
	11.001	3.2	2.000 uA	560.0 V	0.000 uA	0.0 V	Off	

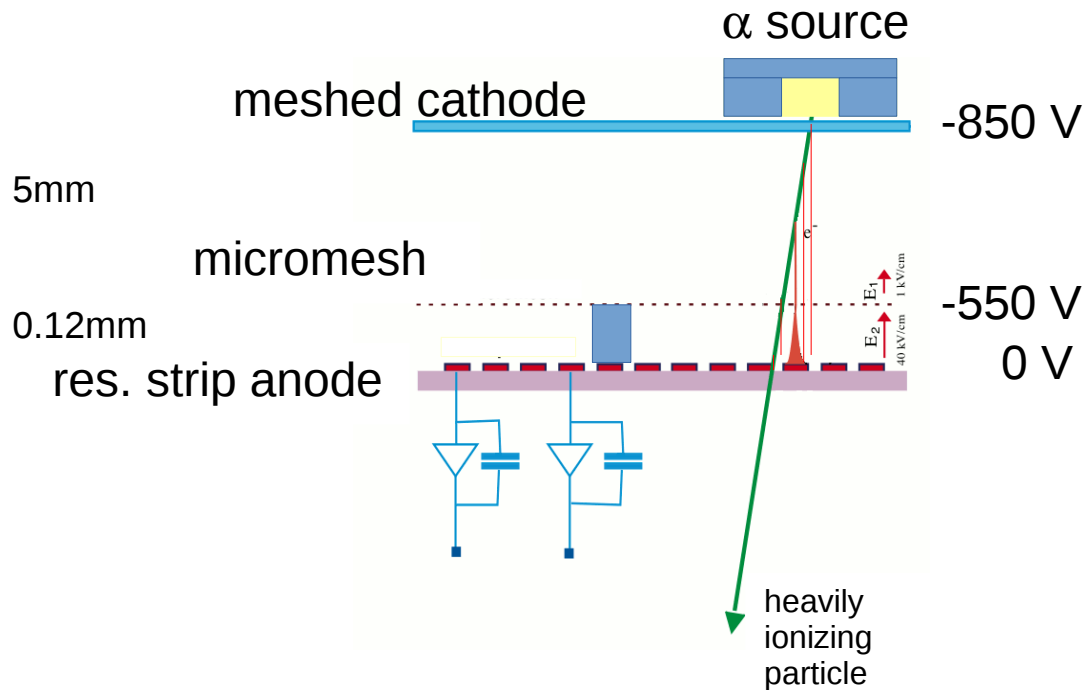
a fully personal review

Ralf Hertenberger, LS Schaile, LMU München
RD51 HV workshop Garching 21. June 2018

Standard Micromegas

Discharges Between Mesh and Anode @ High Charge Density

(non destructive but deadtime inducing)



accelerator physics:
heavily primary ionizing particles
accompany
minimum ionizing muons

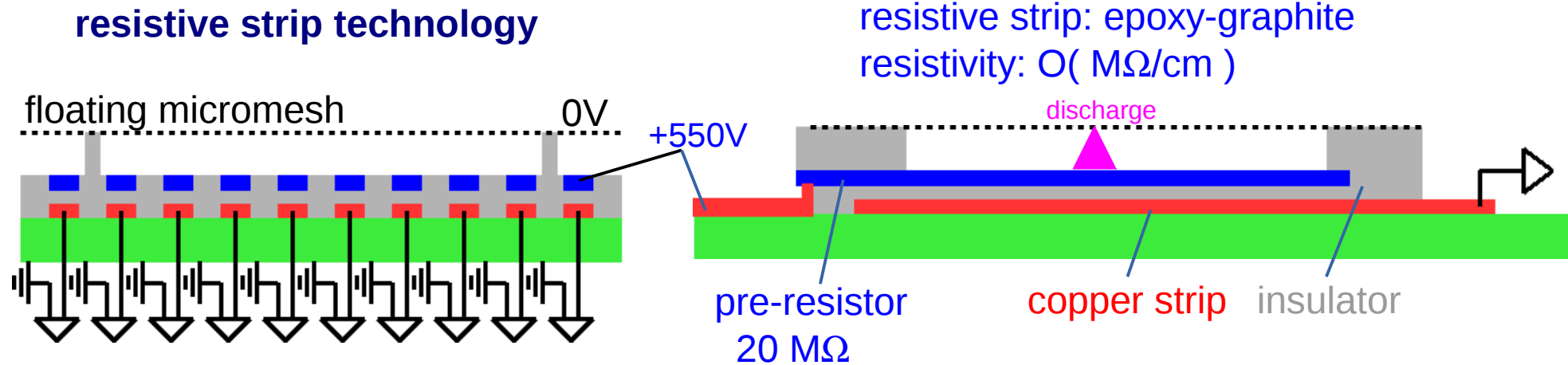
**working point muon detection:
550 V**

**working point α detection:
450 V**

5.8 MeV α induce discharges
@ $3 * 10^8 \text{ e}^-/\text{mm}^2$
Raether limit

↓
discharge protection is necessary

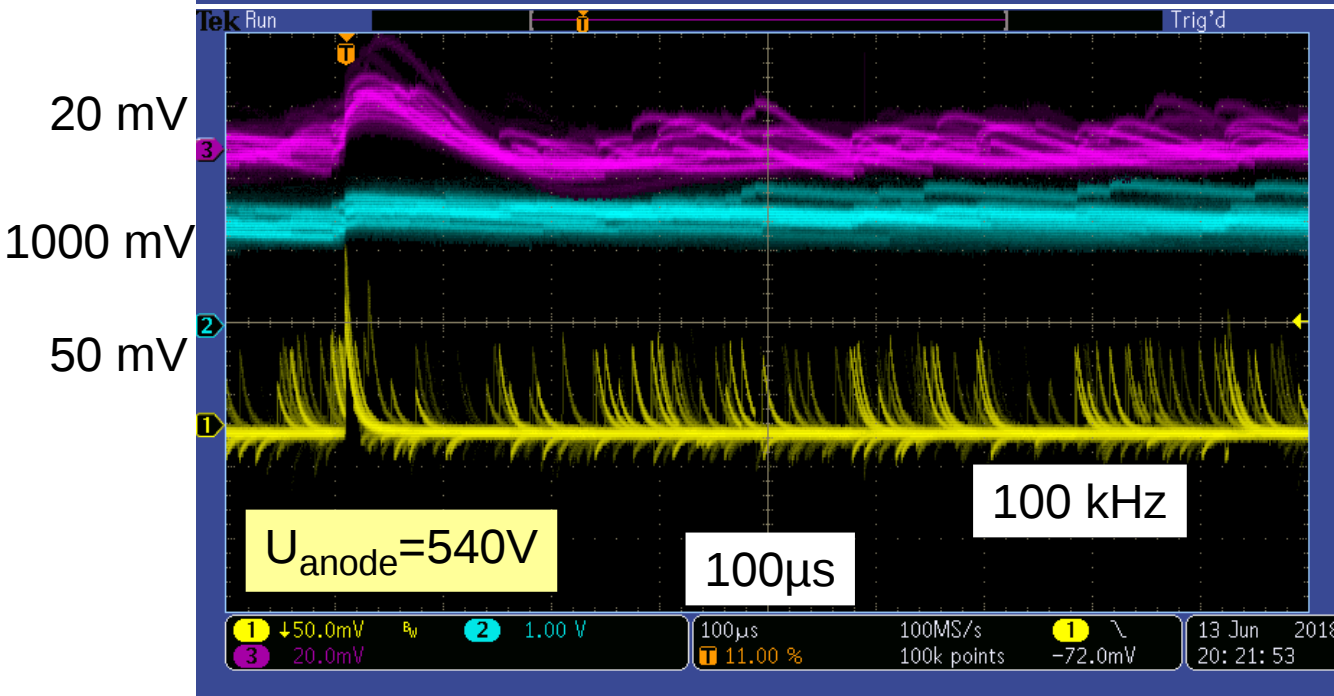
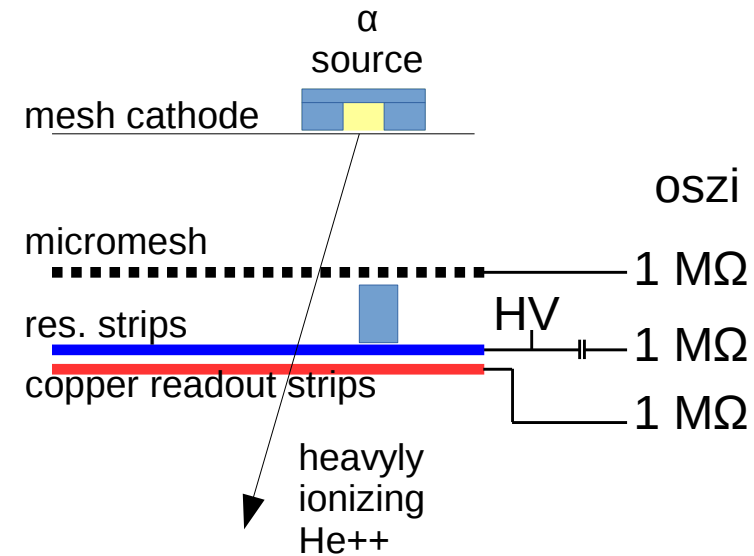
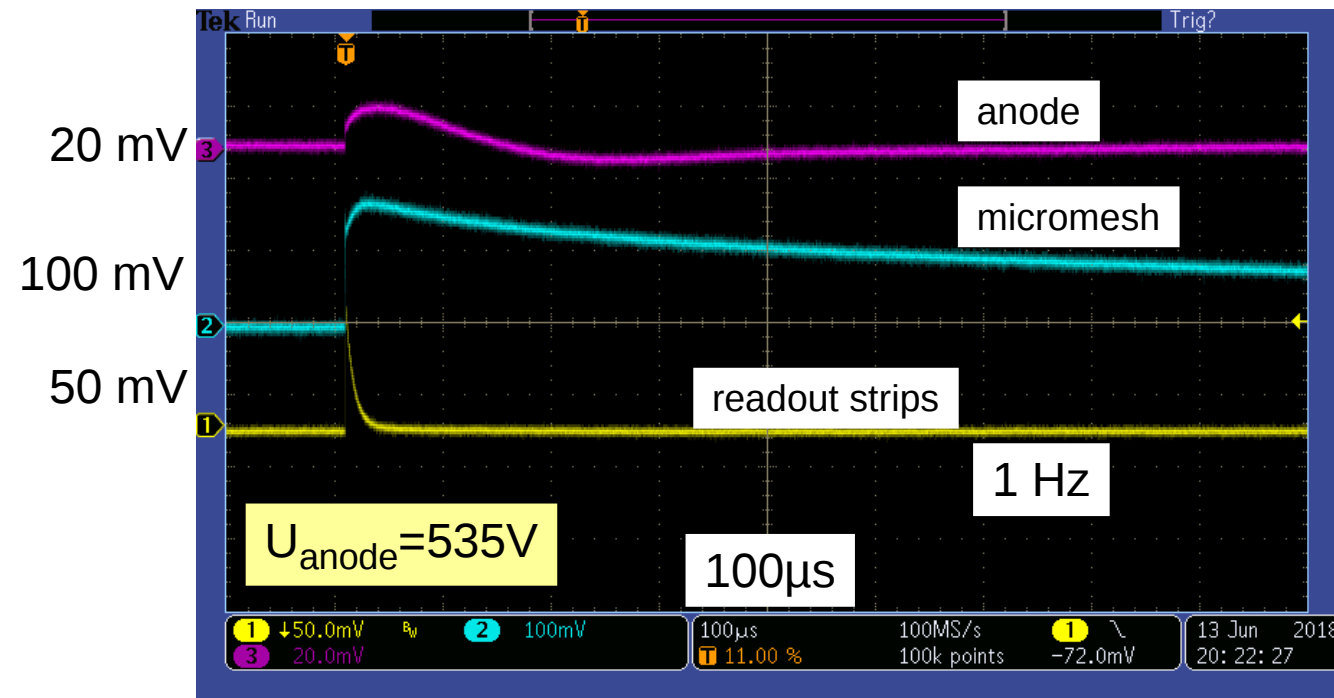
Resistive Strip Micromegas (1D Readout)



potential equilibrium locally around discharge

discharge / streamer is not able to develop fully
restricted to small part of a strip

Discharge Protection Seems to Work (T-Chamber)

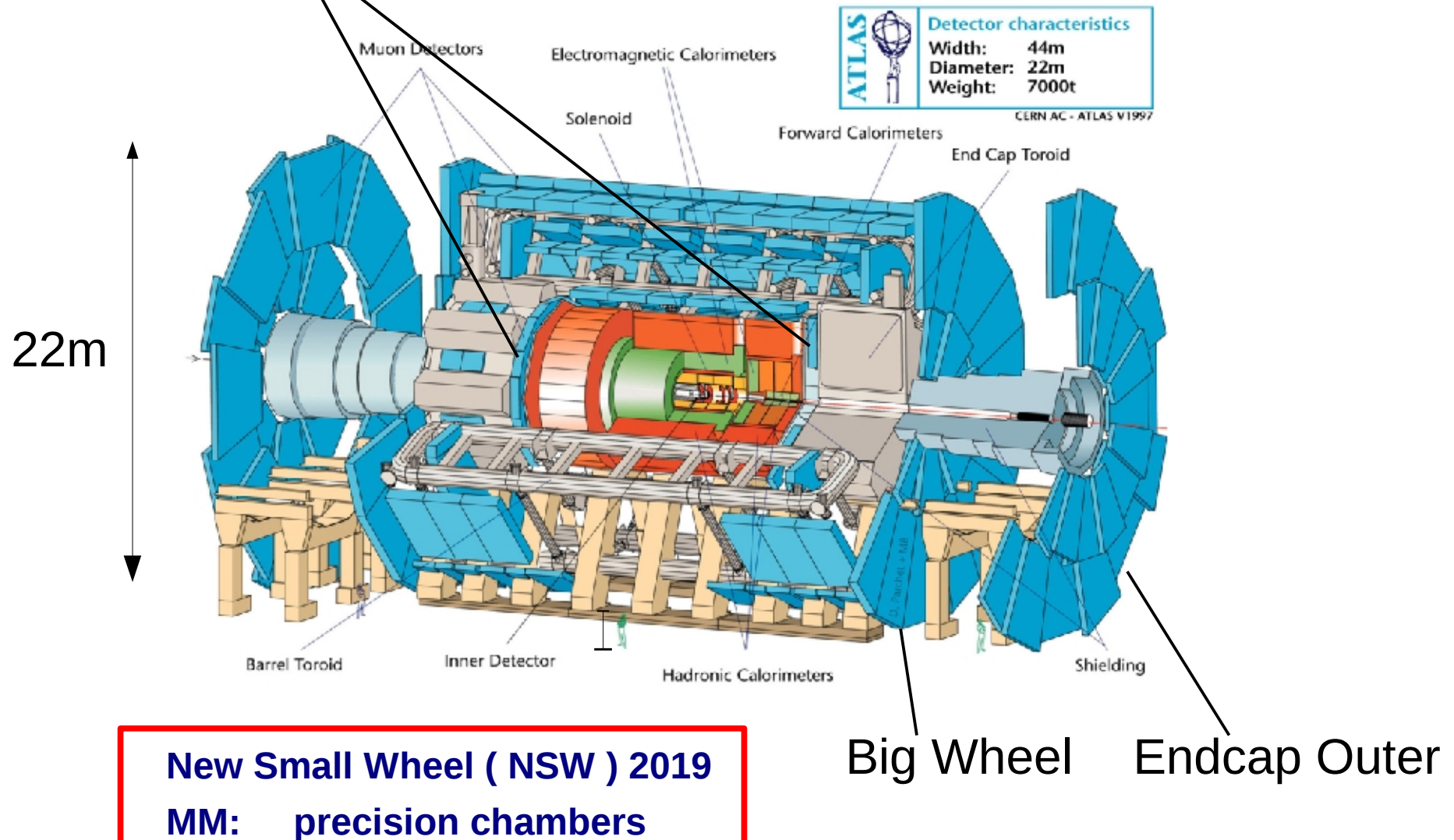


5.8 MeV α induce discharges
@ $3 \times 10^8 \text{ e}^-/\text{mm}^2$
Raether limit

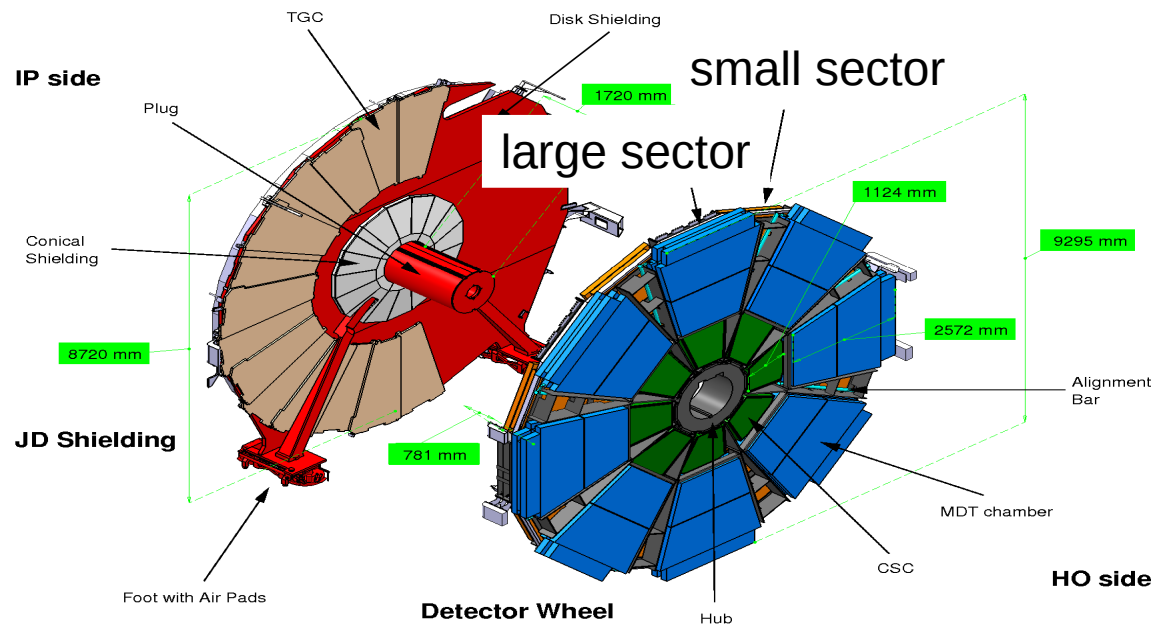
still no substantial change in U_{amp}

ATLAS: Muons Are Accompanied by Strongly Ionizing Background

Small Wheel: highest background rates

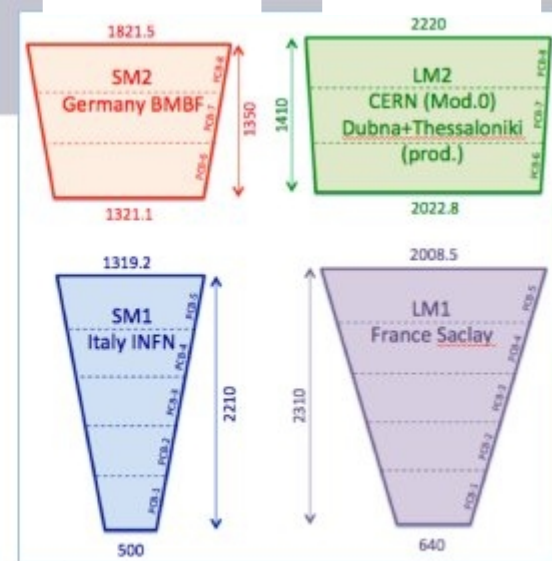


Resistive Strip Micromegas for the ATLAS Muon NSW



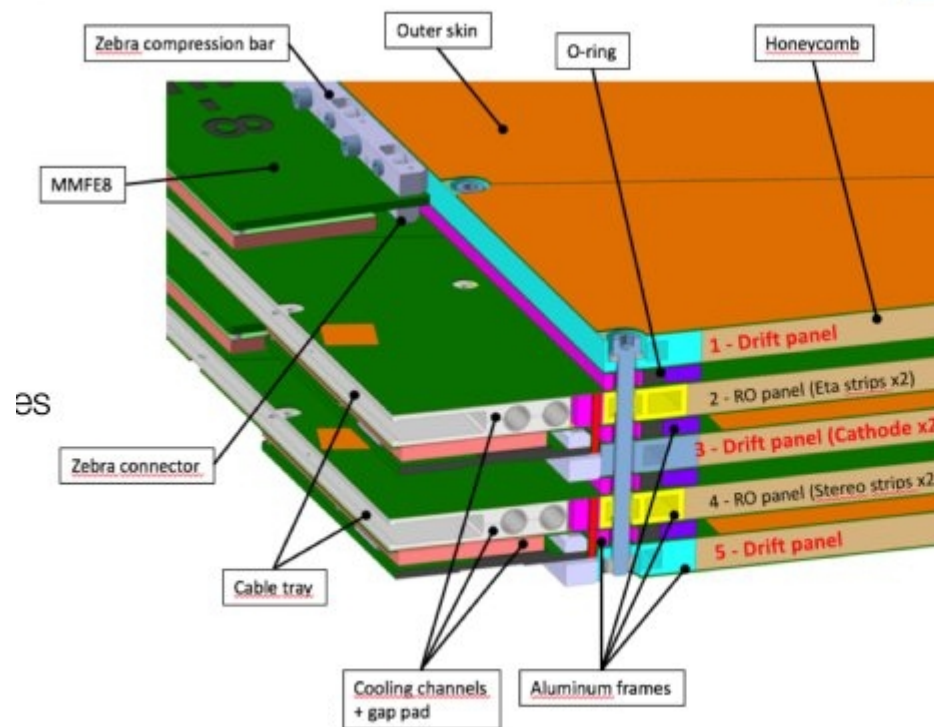
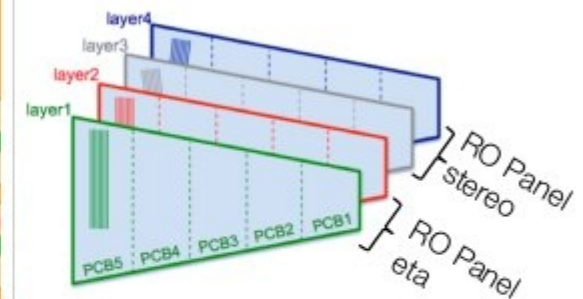
small modules

large modules



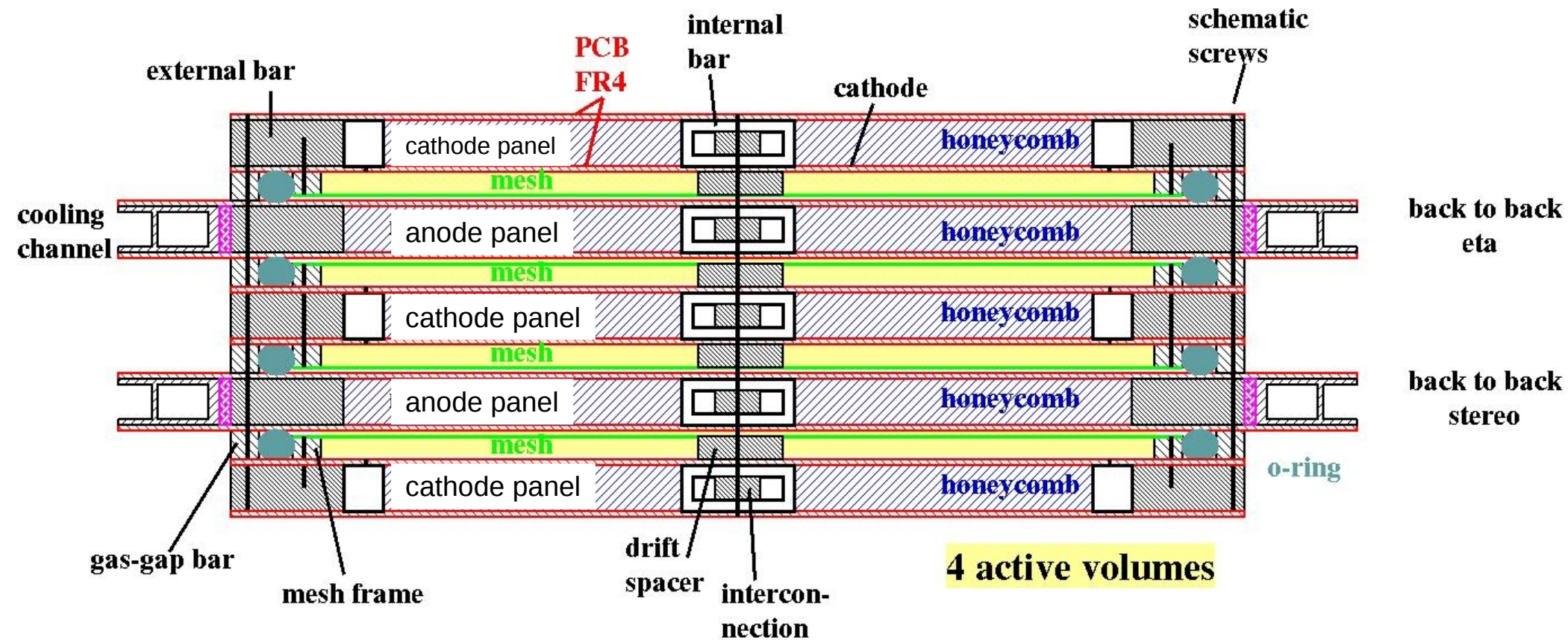
4 active layers

Strips orientation of the 4 RO planes



Schematic of a 2m² Quadruplet

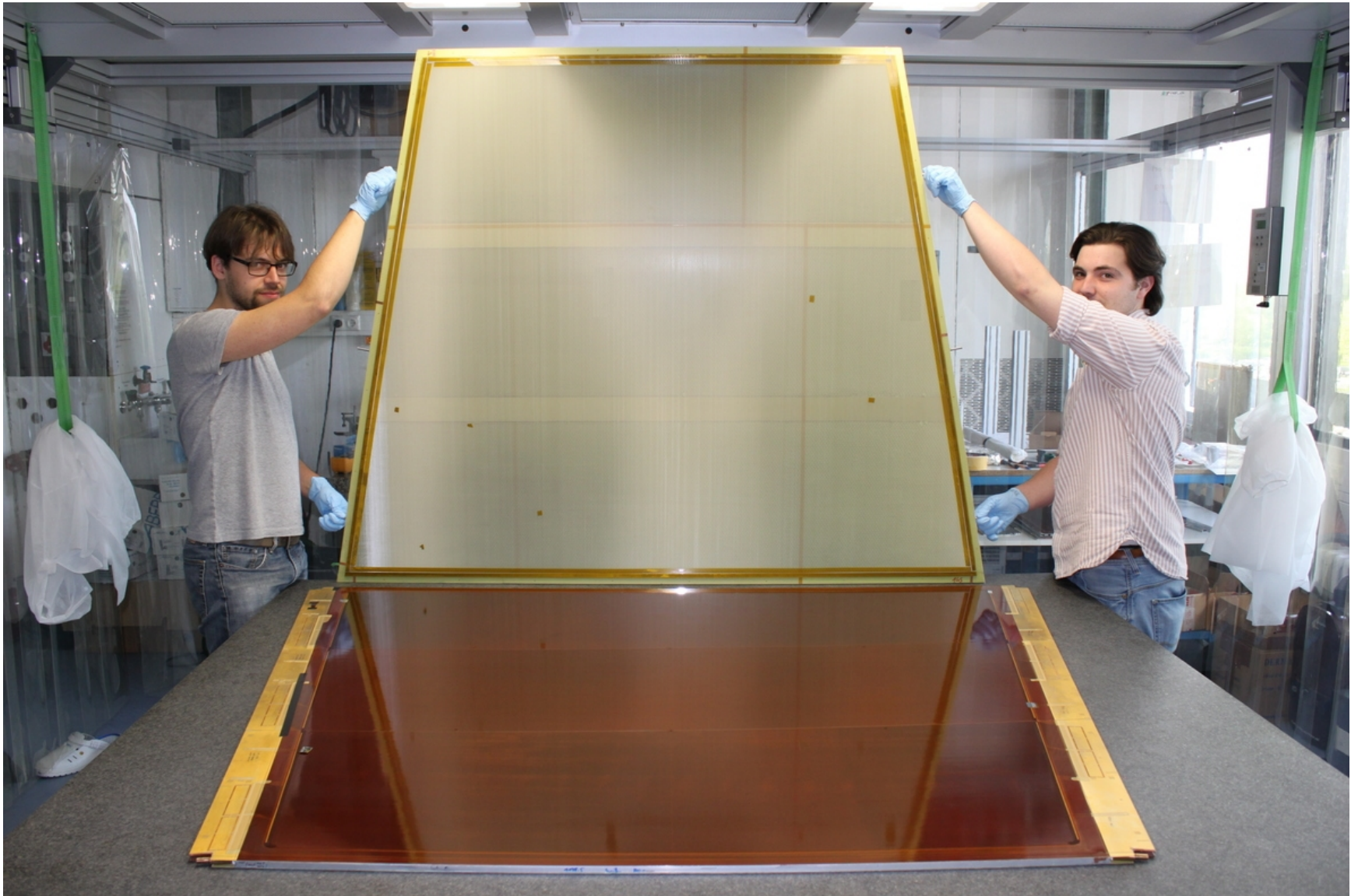
4 active layers



5 honeycomb reinforced sandwich panels
floating grounded mesh (no bulk technology)
mounted on cathode panels
the **active area** is in between drift and readout panels

cathode panel:
with micromesh attached to it
grounded **floating** mesh

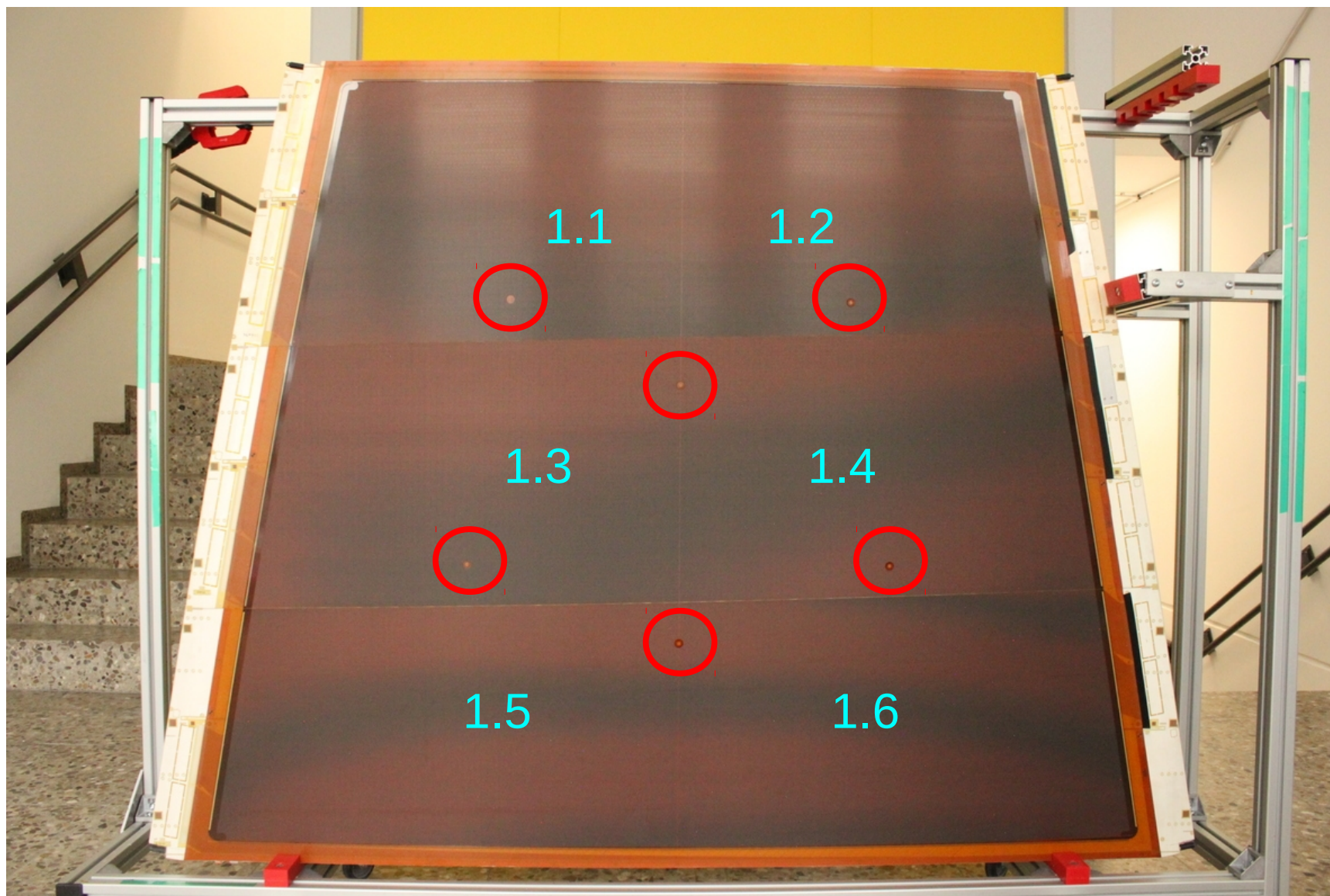
P
R
E
S
R
I
E
S



P
R
E
S
R
I
E
S

microstructured anode panel:
resistive strips with pillars

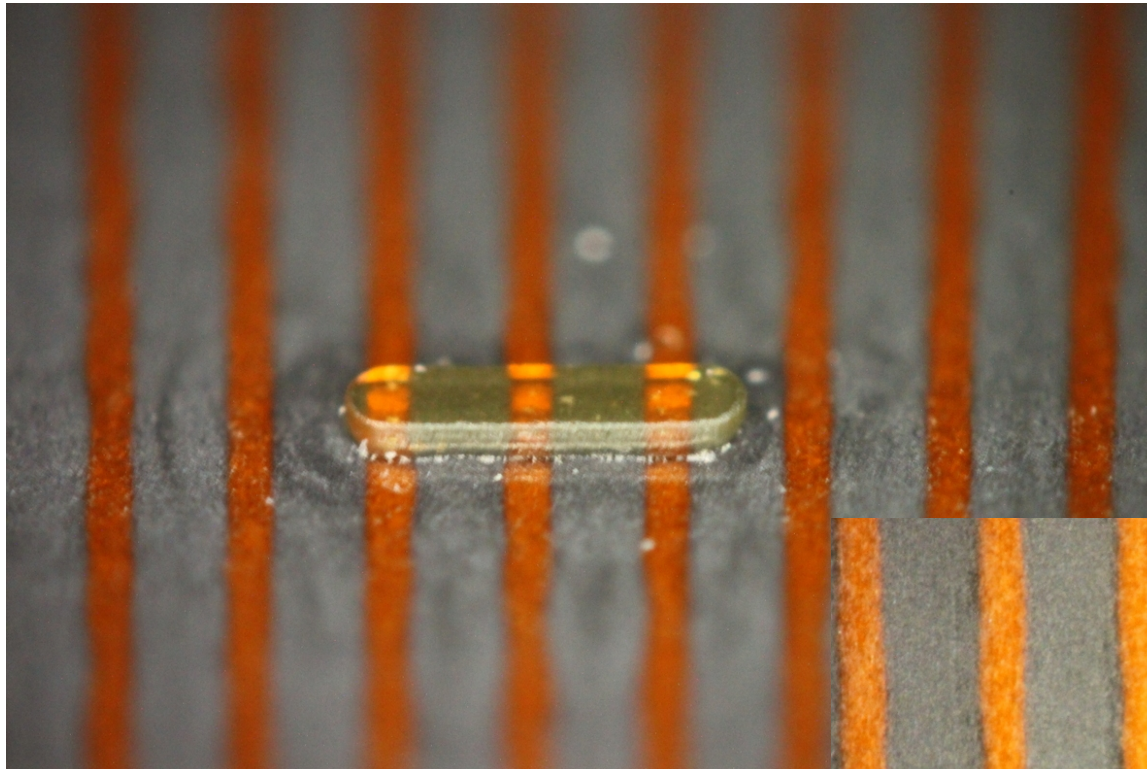
A SM2 Stereo Readout-Panel



3 PCBs
6 HV sectors

3068 strips, 425 μm pitch, 1.5 deg tilted against horizontal direction
120 μm high insulating pillars every 7 mm
6 interconnection regions no blow-up, but also to define floating mesh

120 μm Pyralux Pillars Define the Distance Micromesh - Anode



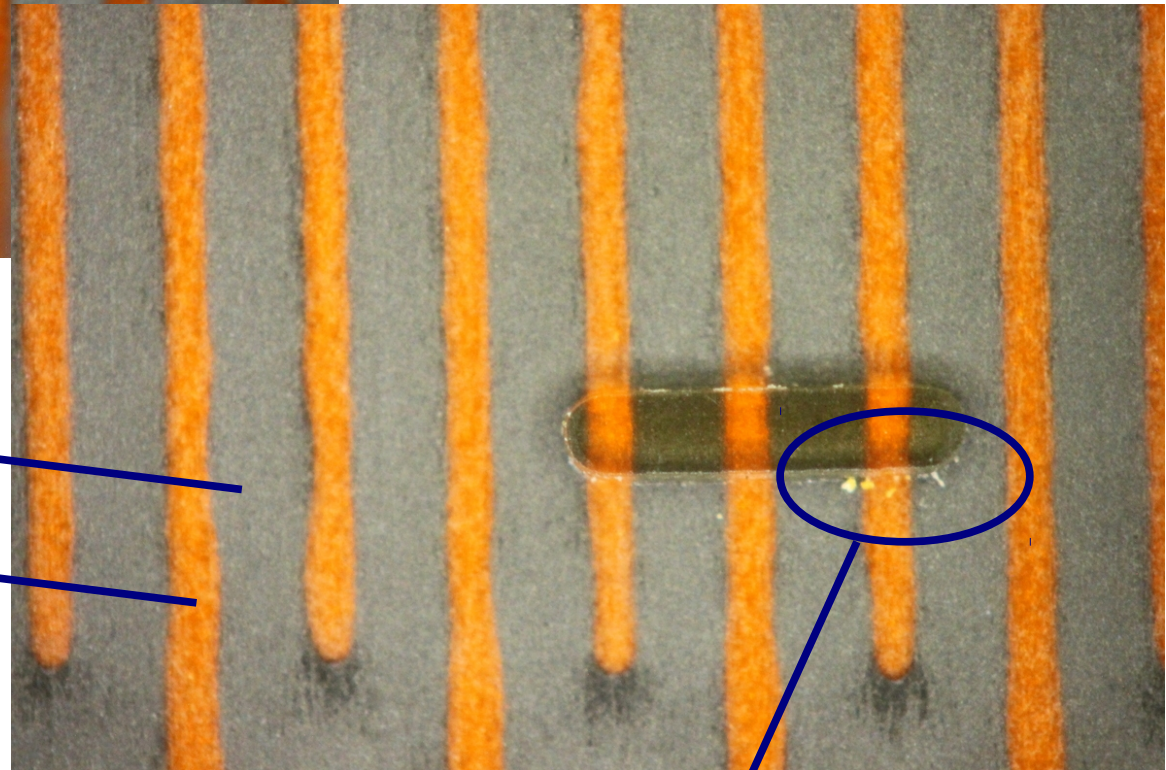
pillar material: Pyralux
O(50000) pillars per plane

dust and dirt concentrates
around the base of the
pillars

=> dedicated washing
procedure

resistive strips

Kapton layer



dirt

inspection



micro crystal cleaner
readout panels



NGL drift panels

micro crystal cleaner
2nd side ro panel



cleaning with deionized water



rinsing with warm tap water + use of brush



SM2 Cleaning @ Cern
total time 1-2h



all 3 panels in Rui's oven

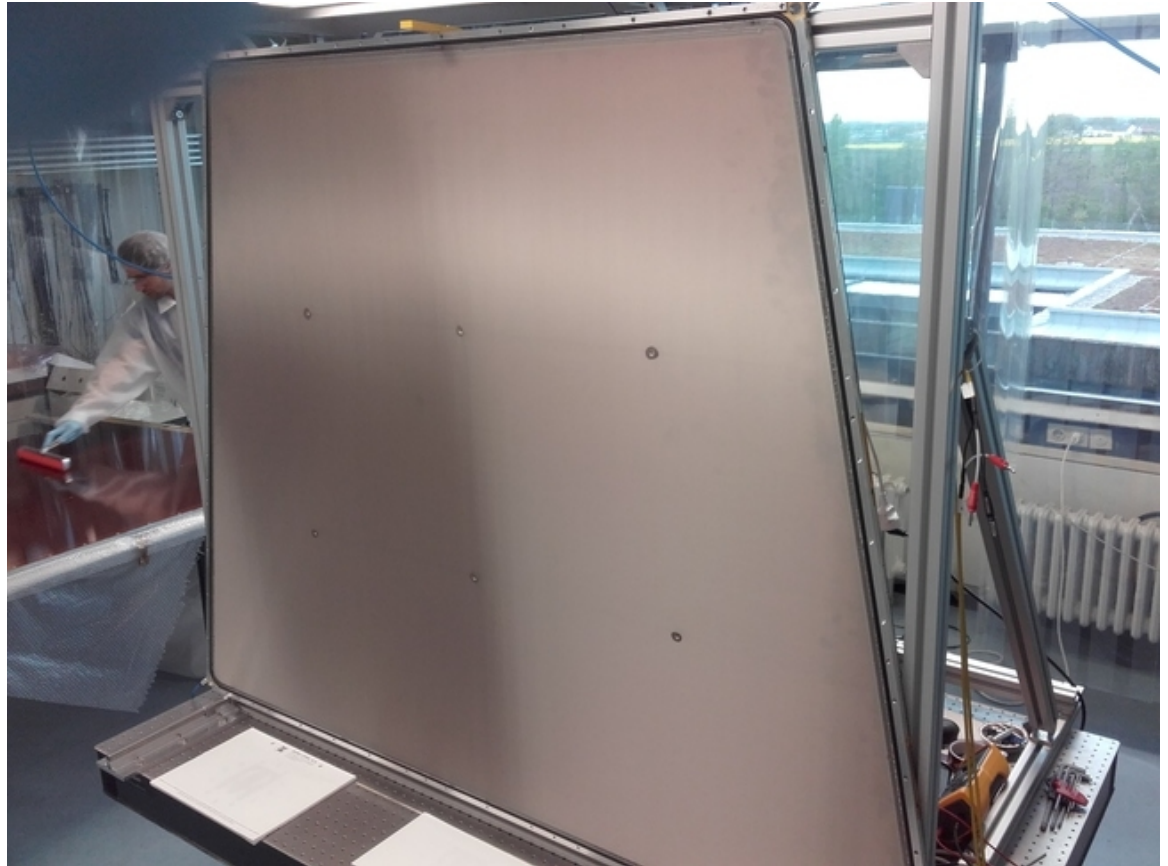
Wet Cleaning:

1. remove remnants from lithographic production processes
2. remove dust and dirt

The Wet Cleaning is implemented at all 4 production sites

It works, all remnants of the lithographic production processes can be efficiently removed

Assembly Station in a Laminar Flow Tent (Iso5)



dry cleaning of an external drift panel using vacuum + brush and the sticky roller

in the background: dry cleaning of a readout panel

Assembly Station



the cleaned readout panel
is placed
against the drift panel

A Completed Quadruplet on the Assembly Station



HV test under dry air starts immediately after assembly
dry air is used to avoid long waiting time for Ar:CO₂ flushing

SM2: Status of Cleaned Multiplets

multiplet	cleaned in	# of wet clean. cycles	dry air	Ar:CO2	# of sectors @ U_{\max}	panels in multiplet
M2 doublet:	Cern	1x	990 V	590 V	12/12	eta2
M1 quplet:	MUC	2x	990 V	560 V	24/24	eta1 / stereo1
M3 doublet:	MUC	1x	975 V	not yet	10/12	stereo 4 + 2x polished ext. drift
eta3:	MUC	1x	not yet	not yet	?	eta3 / stereo 4 + polish. in. drift
M4 quplet:	MUC	0x	under prep.			eta4 / stereo 5 (both glued)

(stereo1, 2, 3 subject to bad SS6 pcbs)

SM2: Status of Cleaned Multiplets

	multiplet	cleaned in	# of wet clean. cycles	dry air	Ar:CO2	# of sectors @ U _{max}	panels in multiplet
1.	M2 doublet:	Cern	1x	990 V	590 V	12/12	eta2
2.	M1 quplet:	MUC	2x	990 V	560 V	24/24	eta1 / stereo1
3.	M3 doublet:	MUC	1x	975 V	not yet	10/12	stereo 4 + 2x polished ext. drift
	eta3:	MUC	1x	not yet	not yet	?	eta3 / stereo 4 + polish. in. drift
	M4 quplet:	MUC	0x	under prep.			eta4 / stereo 5 (both glued)

(stereo1, 2, 3 subject to bad SS6 pcbs)

SM2 M2 Doublet: HV Test under Dry Air in Munich

(cleaned @ Cern, after transport from Cern, no reopening)

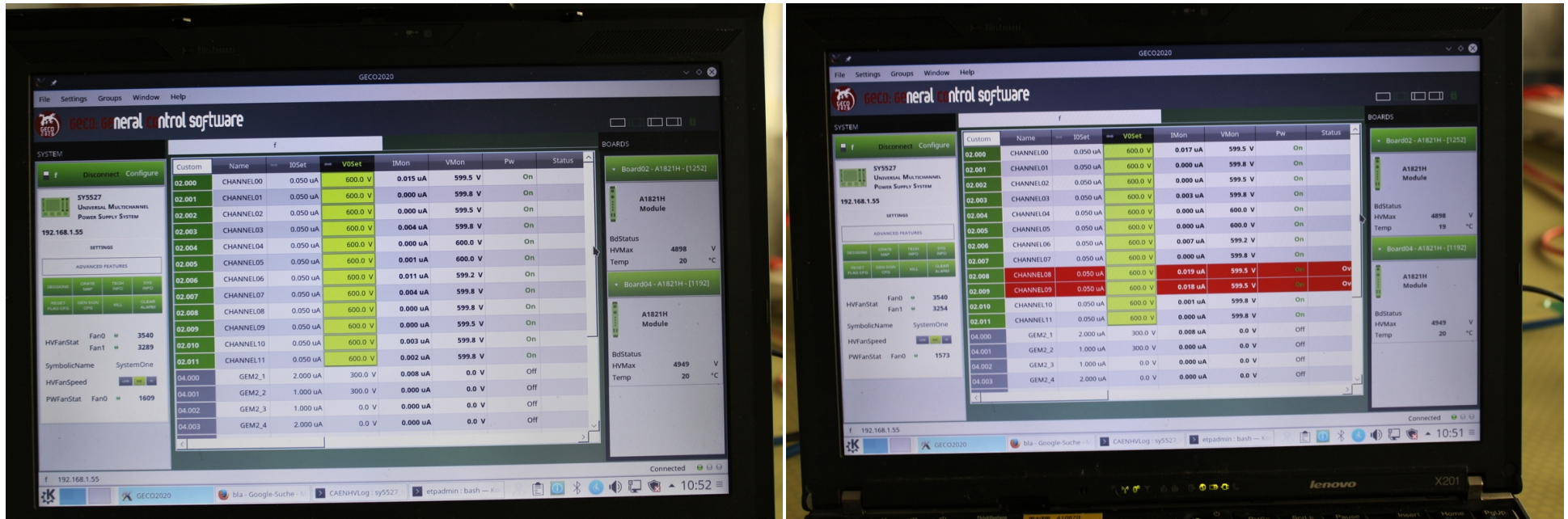
Custom	Name	IOSet	V0Set	IMon	VMon	Pw	Status
02.000	CHANNEL00	0.030 uA	990.0 V	0.016 uA	989.8 V	On	
02.001	CHANNEL01	0.030 uA	990.0 V	0.000 uA	990.0 V	On	
02.002	CHANNEL02	0.030 uA	990.0 V	0.000 uA	989.8 V	On	
02.003	CHANNEL03	0.030 uA	990.0 V	0.004 uA	990.0 V	On	
02.004	CHANNEL04	0.030 uA	990.0 V	0.000 uA	990.0 V	On	
02.005	CHANNEL05	0.030 uA	990.0 V	0.000 uA	990.2 V	On	
02.006	CHANNEL06	0.030 uA	990.0 V	0.012 uA	989.2 V	On	
02.007	CHANNEL07	0.030 uA	990.0 V	0.000 uA	989.8 V	On	
02.008	CHANNEL08	0.030 uA	990.0 V	0.001 uA	989.8 V	On	
02.009	CHANNEL09	0.030 uA	990.0 V	0.000 uA	989.8 V	On	
02.010	CHANNEL10	0.030 uA	990.0 V	0.002 uA	989.8 V	On	
02.011	CHANNEL11	0.030 uA	990.0 V	0.008 uA	989.8 V	On	
04.000	GEM2_1	2.000 uA	300.0 V	0.007 uA	0.0 V	Off	
04.001	GEM2_2	1.000 uA	300.0 V	0.000 uA	0.0 V	Off	
04.002	GEM2_3	1.000 uA	0.0 V	0.000 uA	0.0 V	Off	
04.003	GEM2_4	2.000 uA	0.0 V	0.000 uA	0.0 V	Off	

channel 0 and channel 6 have 10 nA offset

all 12 HV sectors are well below 10 nA
identical result as at Cern after cleaning
but there are short trips every few seconds

990 V seems to be the max. sust. voltage (< breakdown voltage)

SM2 M2 Doublet: HV Test under Ar / CO₂ in Munich 600 V



channel 0 and channel 6 have 10 nA offset

at 600 V some sectors become instable

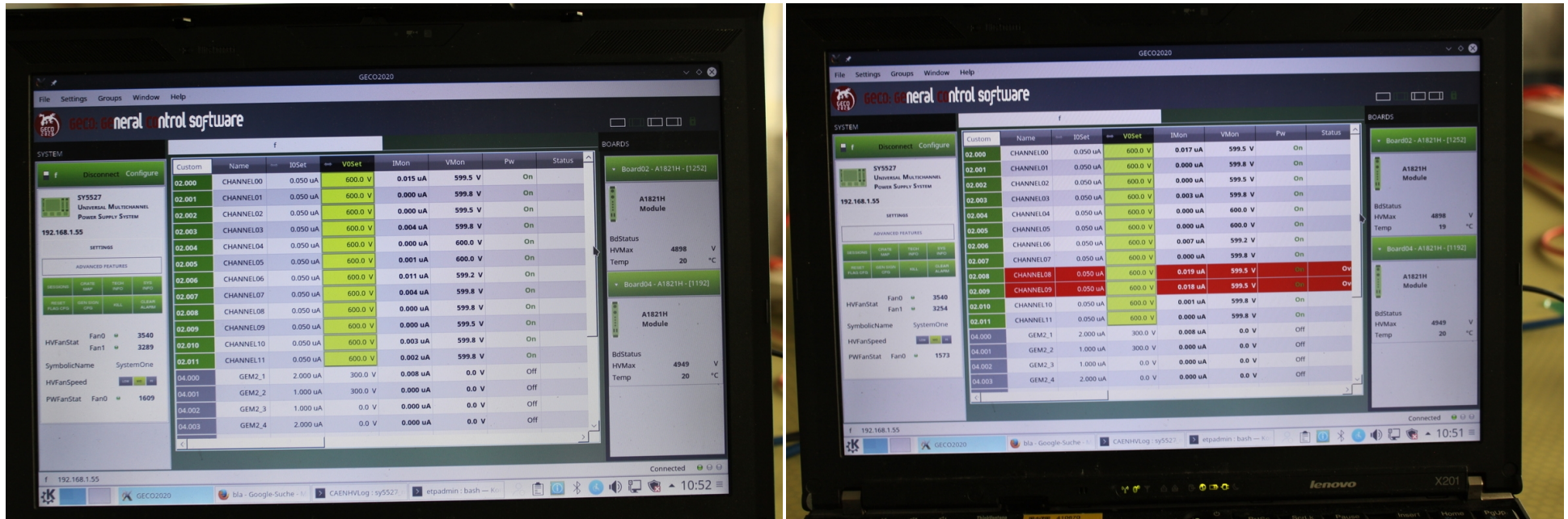
=>

590 V in Ar/CO₂ <=> 990 V in dry Air (pressure dependent)

590 V seems to be the max. sust. voltage for this SM2 doublet

several reopenings and dry cleaning were necessary for this

SM2 M2 Doublet: HV Test under Ar / CO2 in Munich 600 V



channel 0 and channel 6 have 10 nA offset

at 600 V some sectors become instable

=>

590 V in Ar/CO2 <=> 990 V in dry Air (pressure dependent)

590 V seems to be the max. sust. voltage for this SM2 doublet

several reopenings and dry cleaning were necessary for this

SM2 M2 Doublet in the Cosmic Ray Facility Ar:CO2 93:7

5. 4. 2018 - 26. 4. 2018

540 V - 580 V (590 V)

SE6

SE7

SE8 incident during transport

600 V

1.1

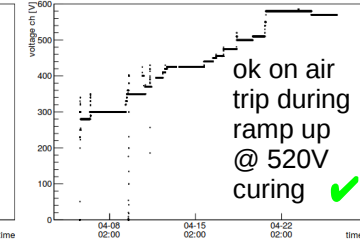
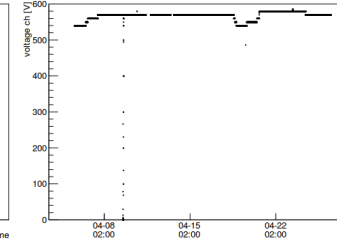
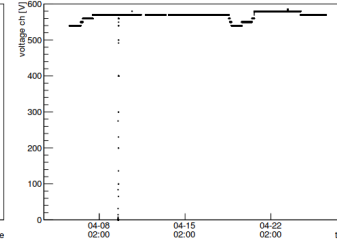
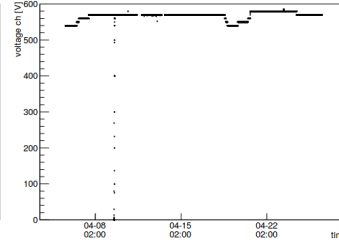
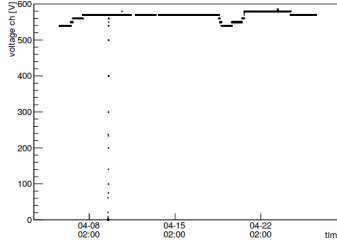
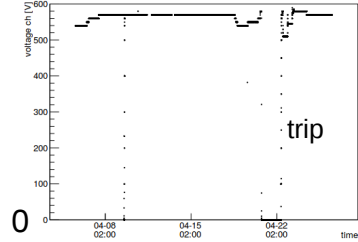
1.2

1.3

1.4

1.5

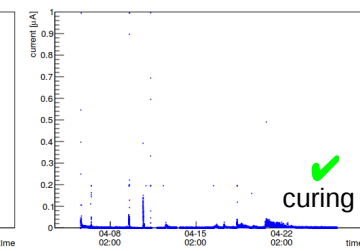
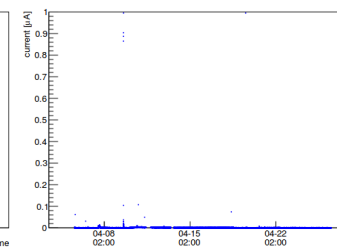
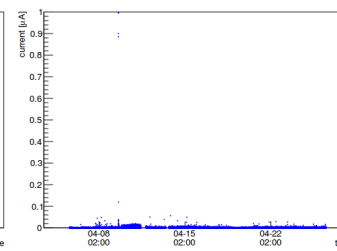
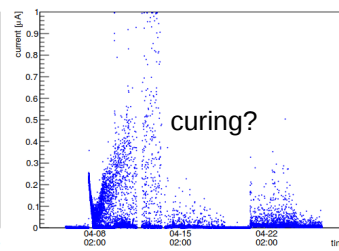
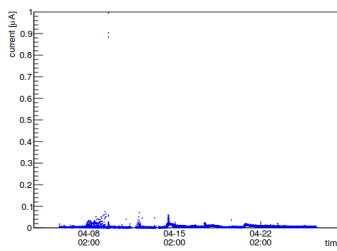
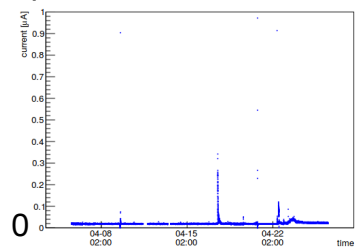
1.6



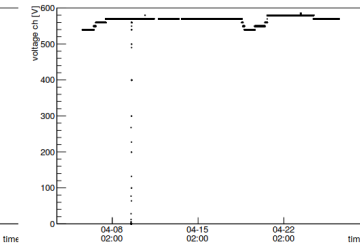
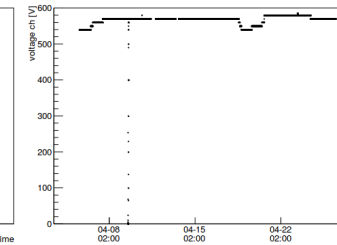
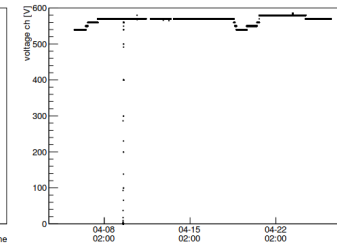
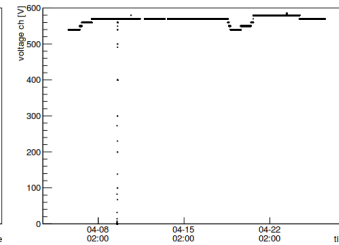
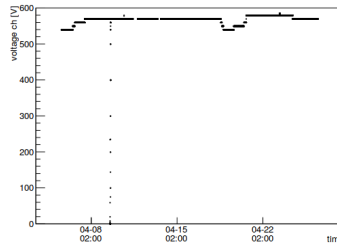
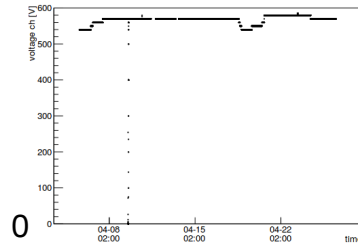
1 μ A

21 days

eta_1



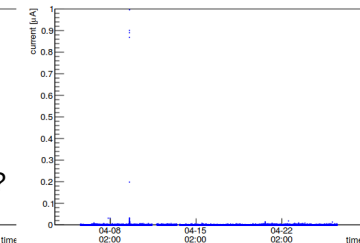
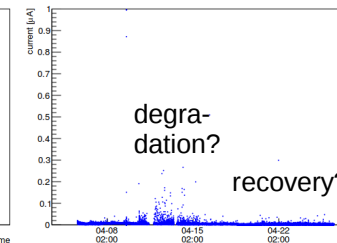
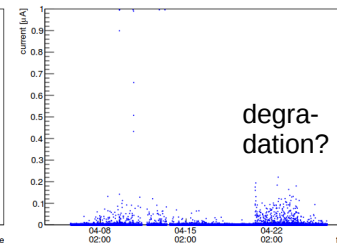
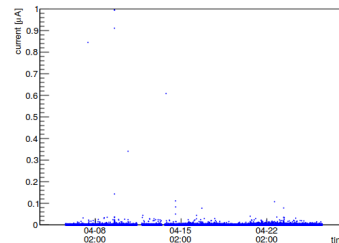
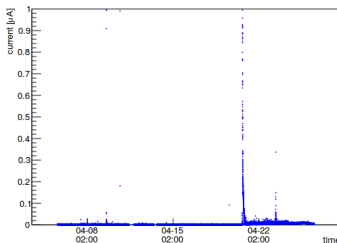
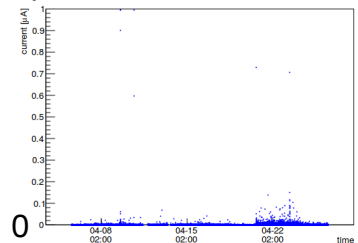
600 V



1 μ A

21 days

eta_2



2.1

2.2

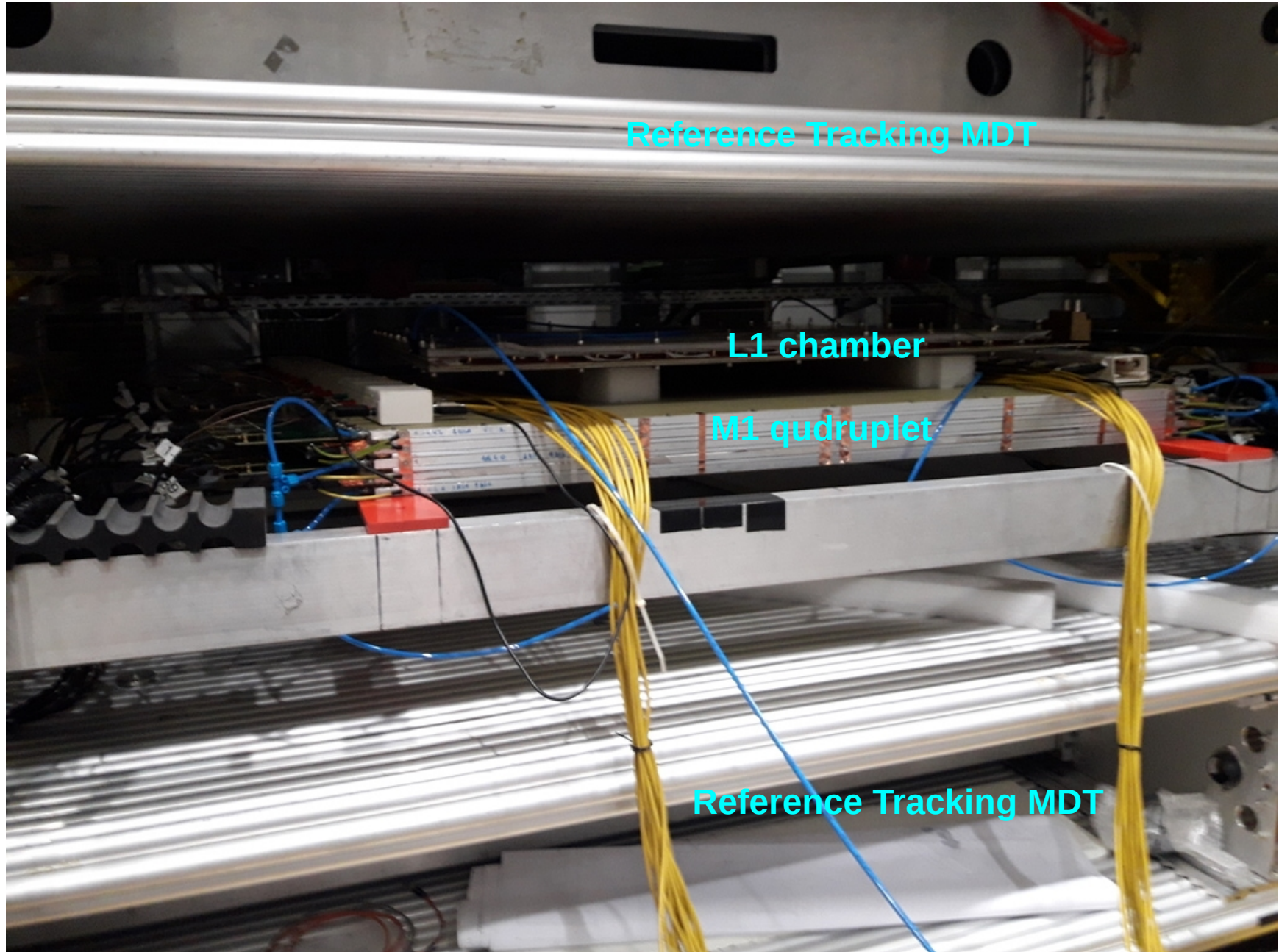
2.3

2.4

2.5

2.6

The M1 Quadruplet in the Munich Cosmic Ray Facility

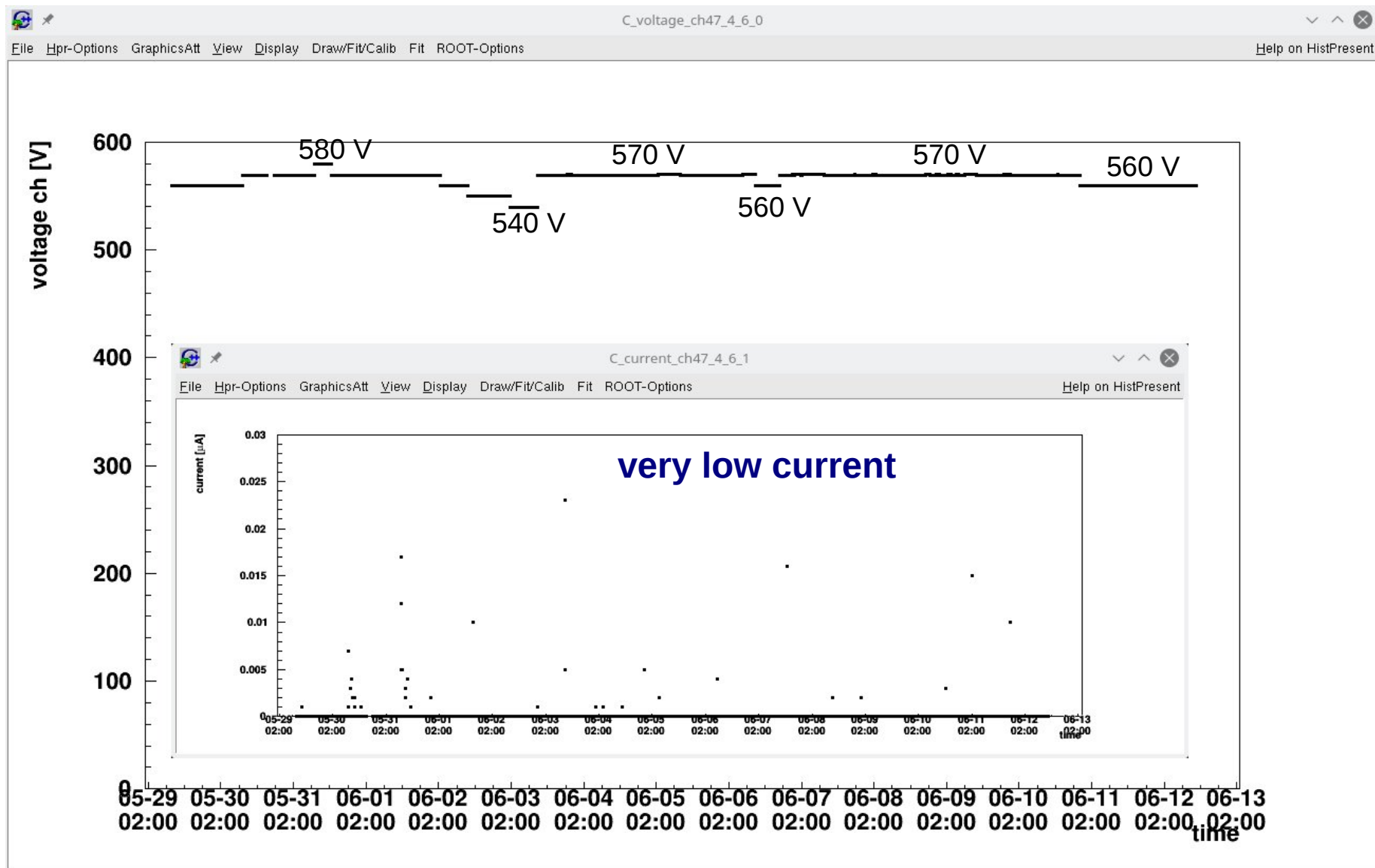


Full APV electronic readout

SM2 M1 Quadruplet in the Cosmic Ray Facility Ar:CO2 93:7

29. 5. 2018 - 12. 6. 2018 540 V - 580 V

timescale of the HV scan in the CRF: e.g.: SE8 Eta_out

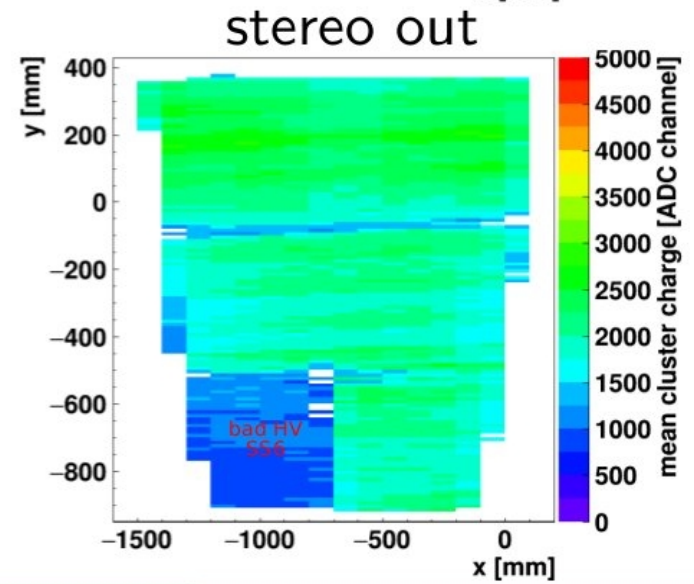
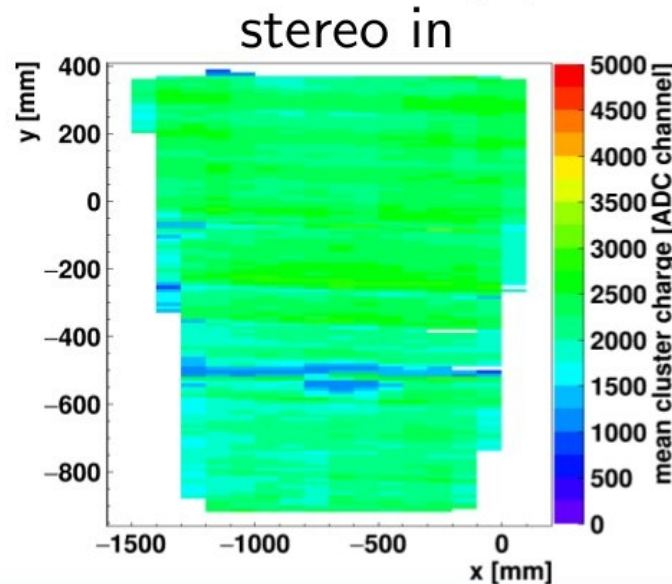
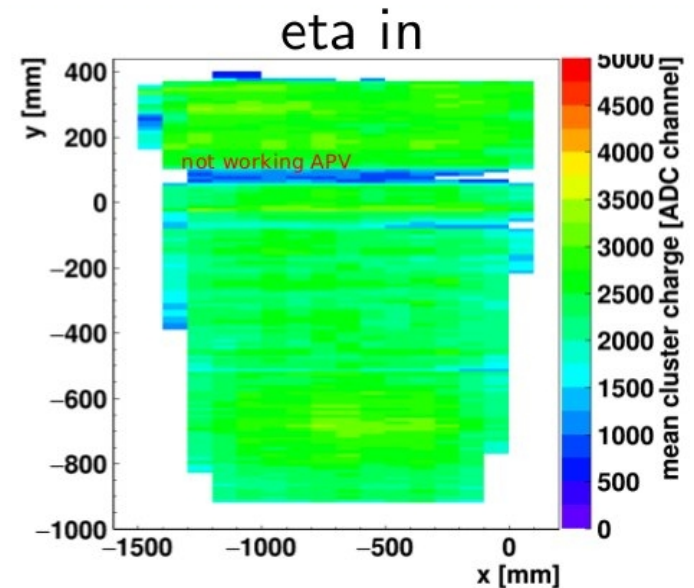
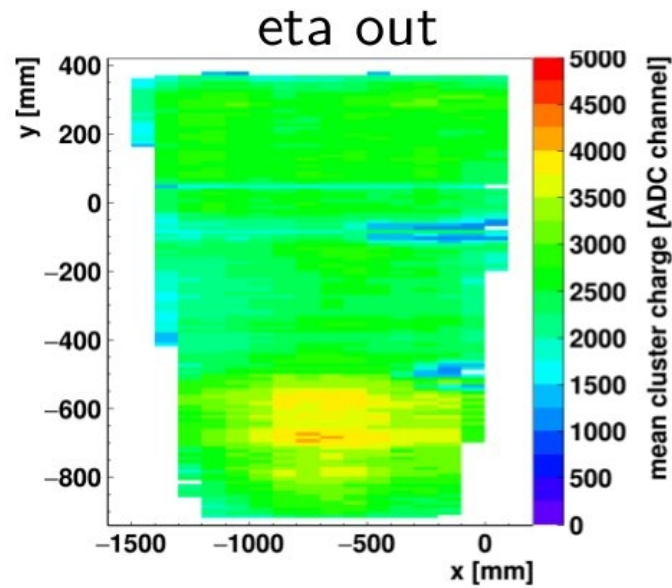


580V was not long term stable ↔ environmental influence?

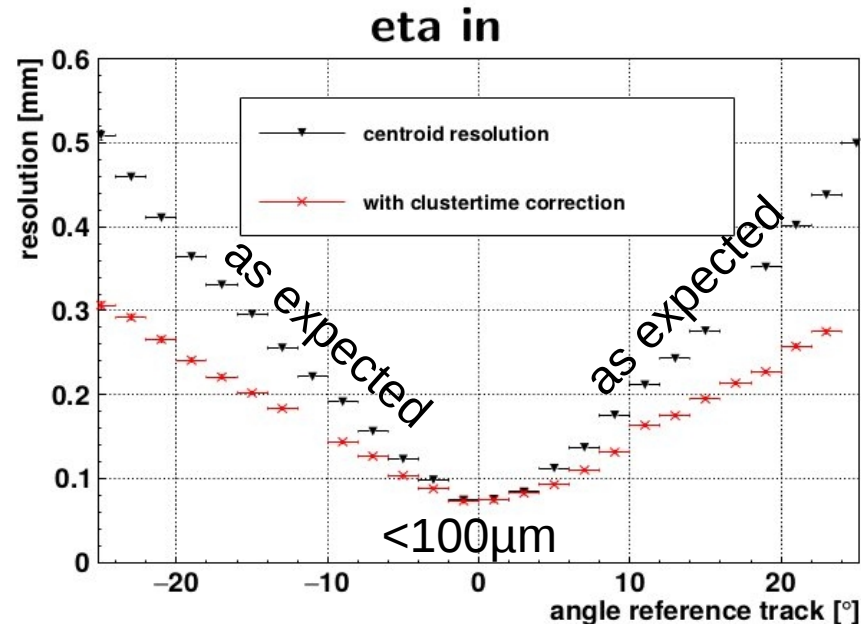
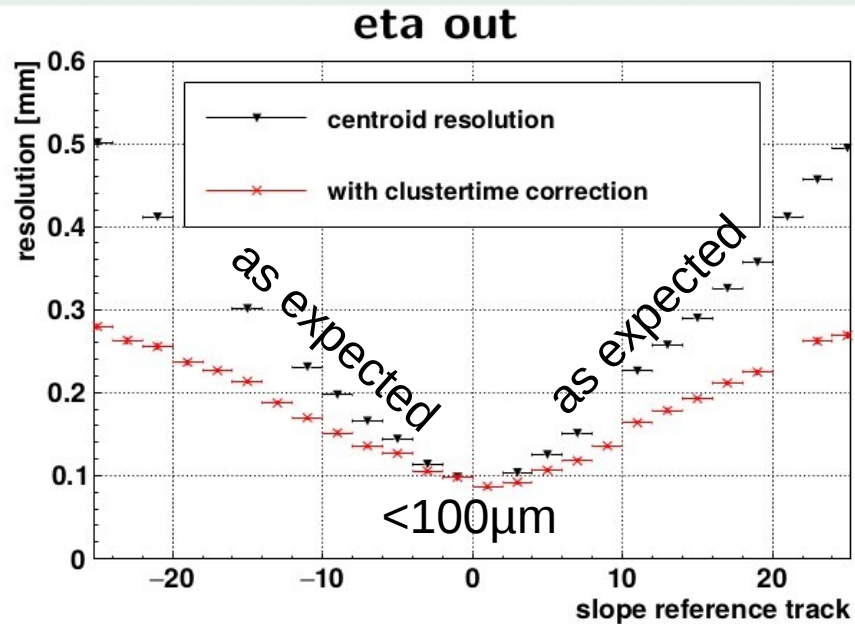
1 SS6 HV sector became bad after short time defective pcb many missing pillars problem solved

SM2 M1: Cosmic Ray Facility Data

Anode : 570 V, Cathode : 300 V, Ar:CO₂ 93:7 vol%
Mean Cluster Charge



Position Resolution as Function of the Incident Angle



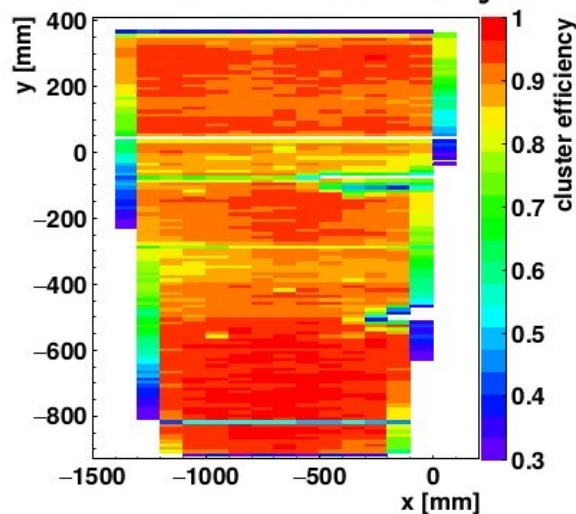
- residual distribution for each angle separately
- fit with double Gaussian
analysis sigma narrow Gaussian only
(reject multiple scattering)
- consider track uncertainty of reference chambers:

$$\sigma_{\text{micromegas}} = \sqrt{\sigma_{\text{res}}^2 - \sigma_{\text{track}}^2}$$

- resolution is for perpendicular incident close to expectation
- charge weighted clustertime correction improves residual distribution considerably
analysis ongoing:
0.2 mm @ 20° expected
(see B.Flierl PhD thesis - Particle Tracking with Micro-Pattern Gaseous Detectors)

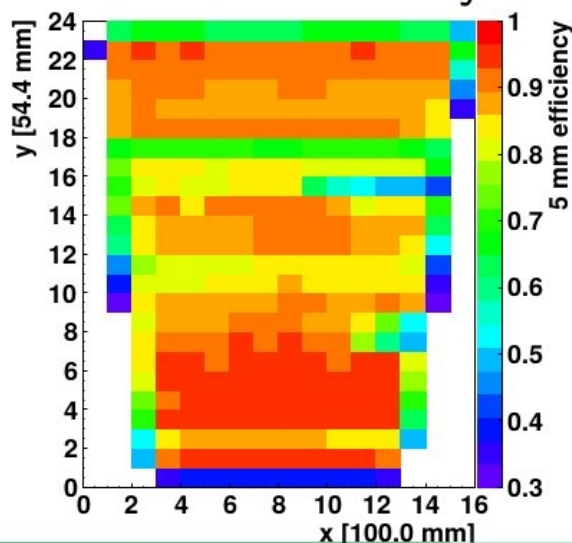
Efficiency (Preliminary)

amplification 570 V, drift 150 V
cluster efficiency

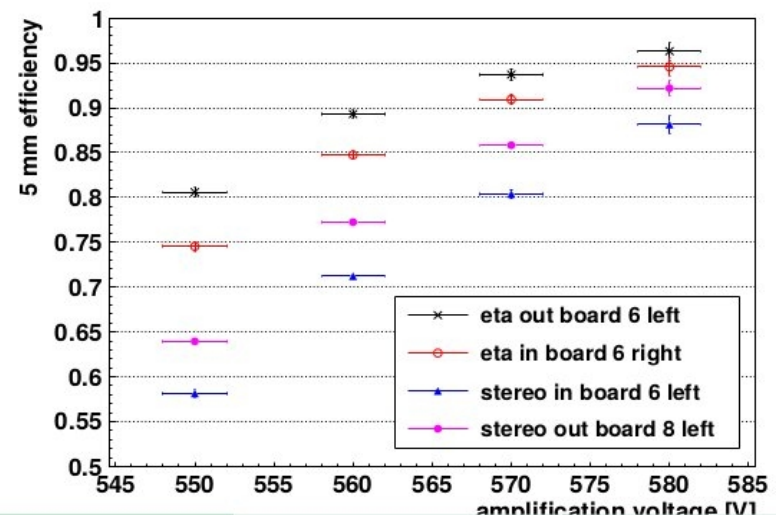


eta_in

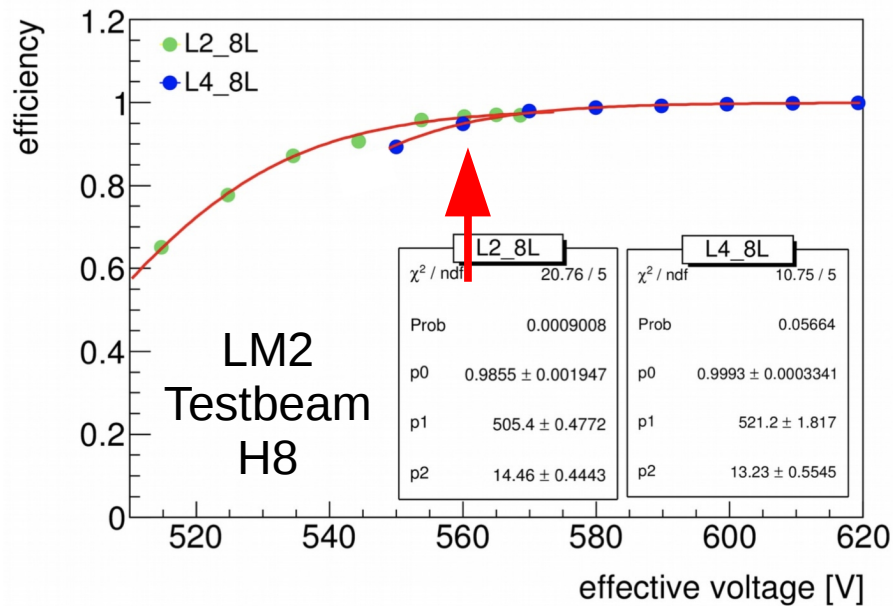
5 mm efficiency



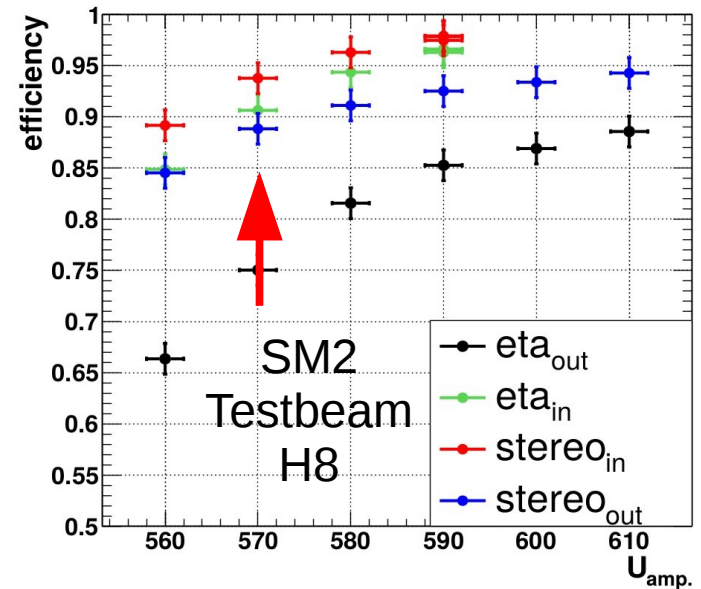
- preliminary results
⇒ cuts have to be checked
- cluster efficiency:
number of cluster with at least 2 strips
divided by number all of tracks going
through partition
- 5 mm efficiency:
number of cluster within 5 mm to track
prediction
divided by number of all tracks going
through partition
- efficiency decreased by missing
strips / zebra?



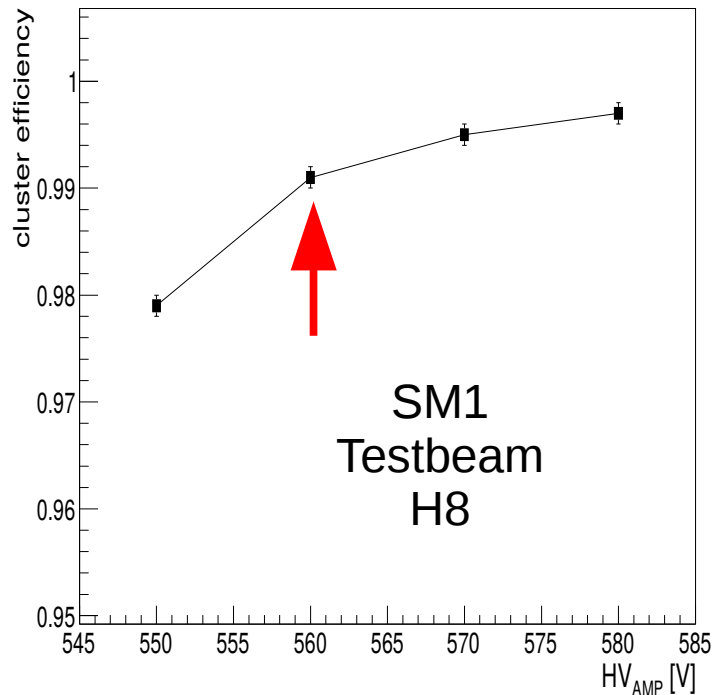
Efficiency Turn On Curves for Module 0



screen printed res. strips



sputtered resistive strips



efficiencies were in the plateau above 560-570 V

stable situation

higher primary ionisation than MIPs

20. April 2018 Summary of the Facts:

working point: 560 - 580 V

max voltage: 590 - 600 V

the small dynamic range between 580 and 590 V
is driving the question:

**can we increase the margin between work.point and max.voltage
by**

- 1. increasing the break down voltage**
- 2. lowering the working point**

=>

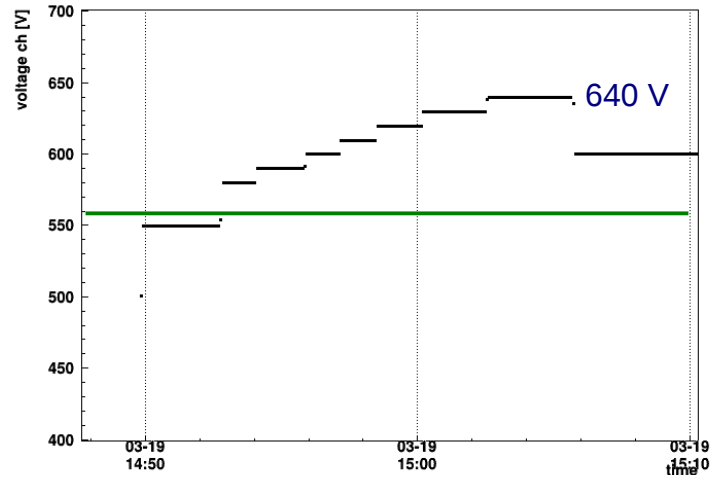
compare with

1. data from T-chamber (18/45 calendered mesh)
2. data from ExMe chamber (F.Kuger 2016) similar to SM2
(ExMe: exchangeable mesh)

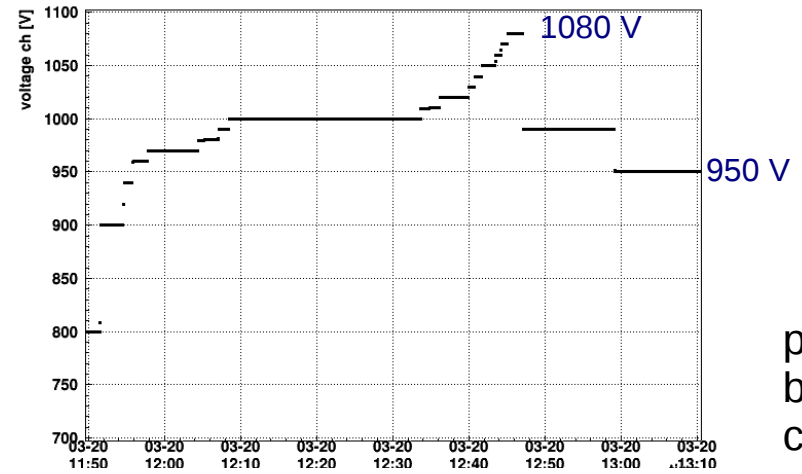
HV Max. Voltages and Currents T-Chamber 19. 3. 2018 (RH + PL)

(the T-chamber was connected to the output of the SM2 Multiplet)

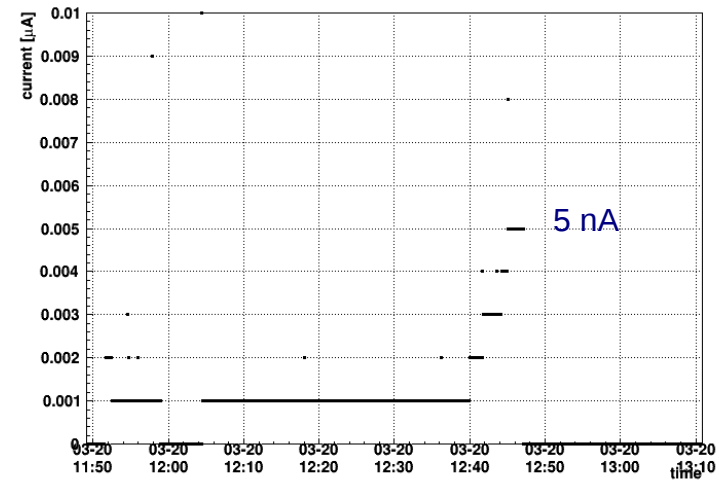
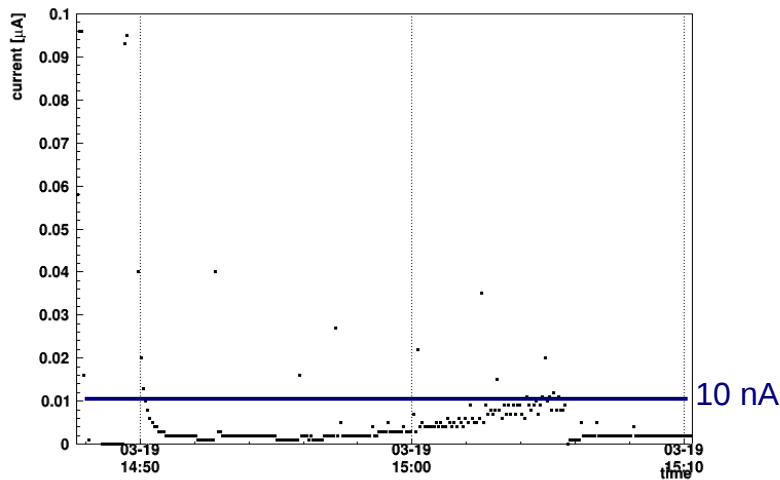
Ar / CO2



Air dry



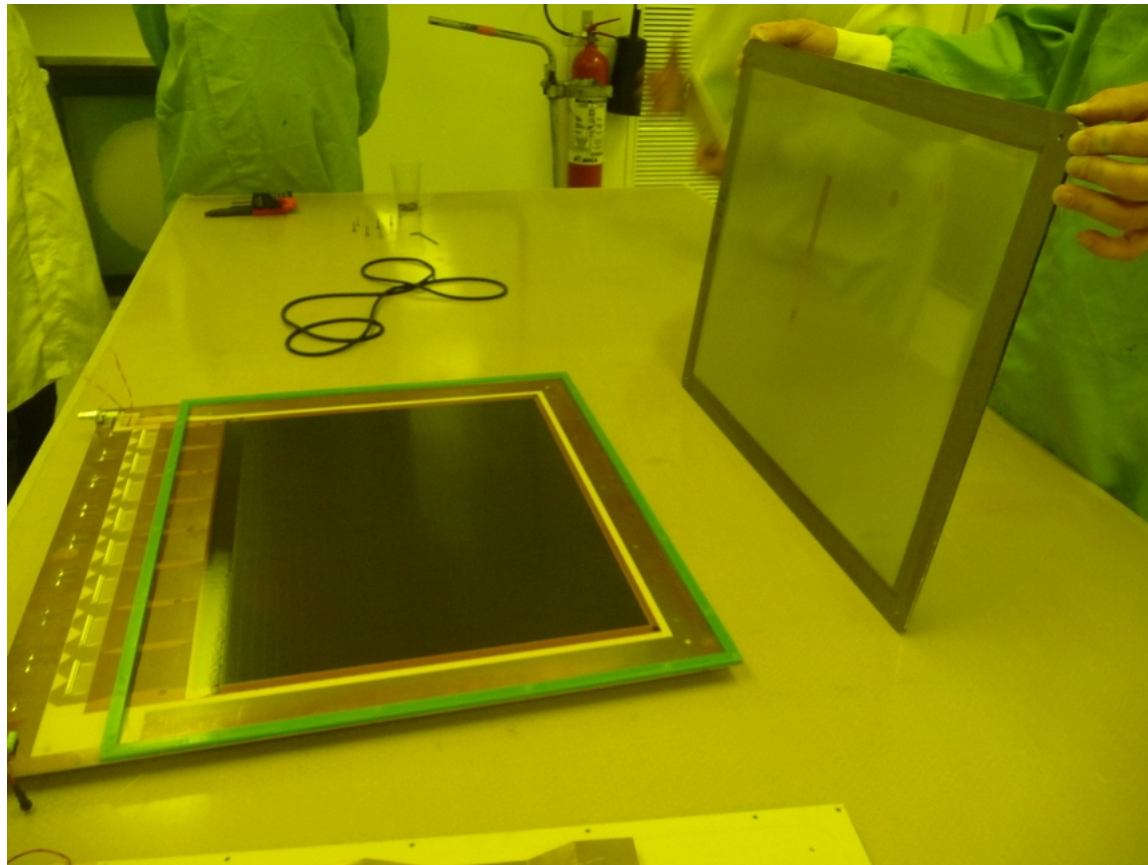
perfectly
behaving
chamber



current rises
smoothly
above
threshold
voltage

	work. point V	max. voltage	pillar height	mesh dimensions	mesh type
T-chamber	520	620	105 μm	18/45 calendared	bulk
NSW MM	570	590	120 μm	30/71 non-calendared	floating mesh

The ExMe Chamber



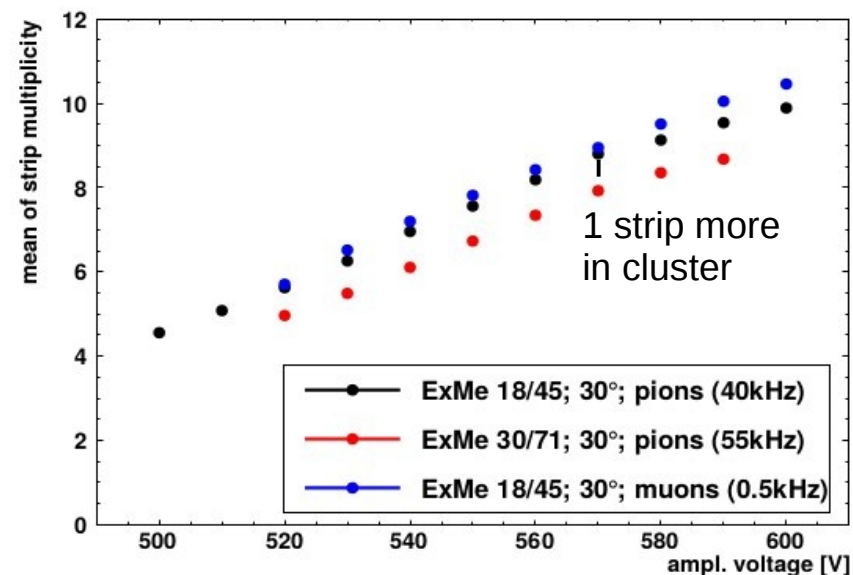
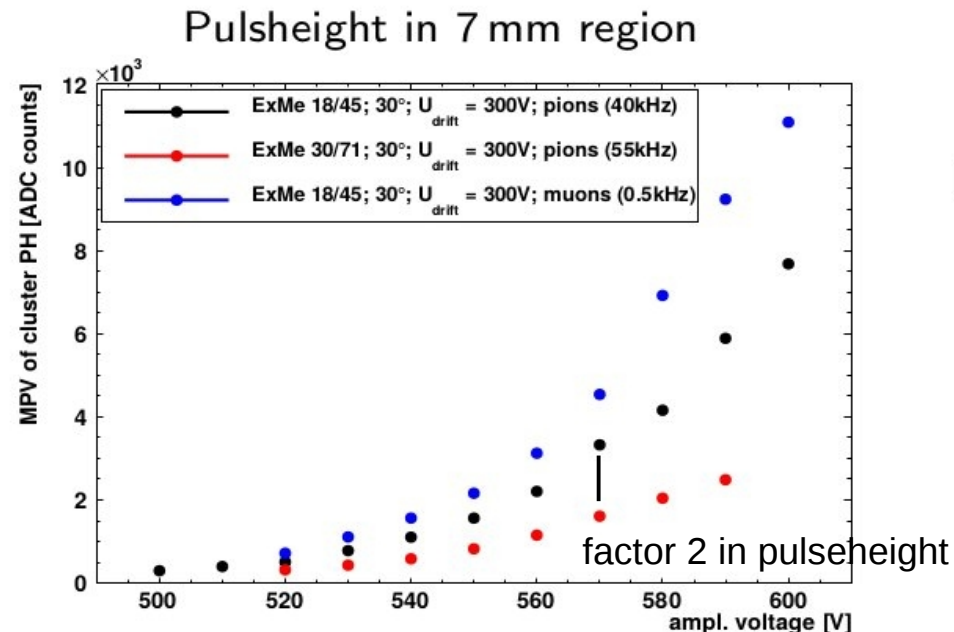
anode similar to NSW MM 120 μm high pillars, 7mm distance
easy to exchange meshes
under otherwise unchanged conditions

the 30/71 mesh has been polished, see later

Pulseheight (mesh comparison)

18/45 calendared mesh
30/71 polished mesh

Mesh comparison:

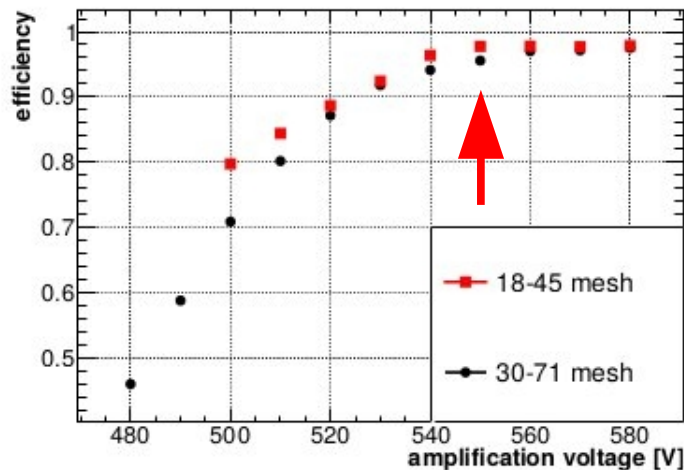


- Pulseheight measured in 7 mm pillar region, here shown @ 30°
- (18-45) μm mesh shows significantly higher amplification than (30-71) μm mesh
- Factor 2 @ 570 V
- Higher working point of (18-45) μm mesh (due to Kapton passivation ?)
- On average higher strip multiplicity at (18-45) μm mesh

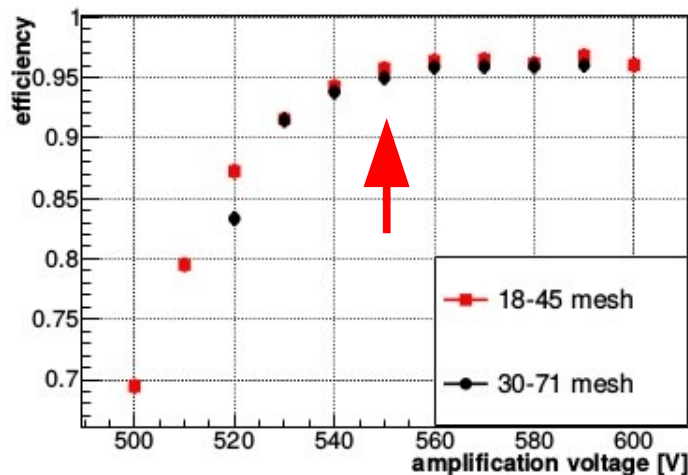
in agreement with Cern Fe55 ExMe results

5 mm Efficiency

0° inclination



30° inclination



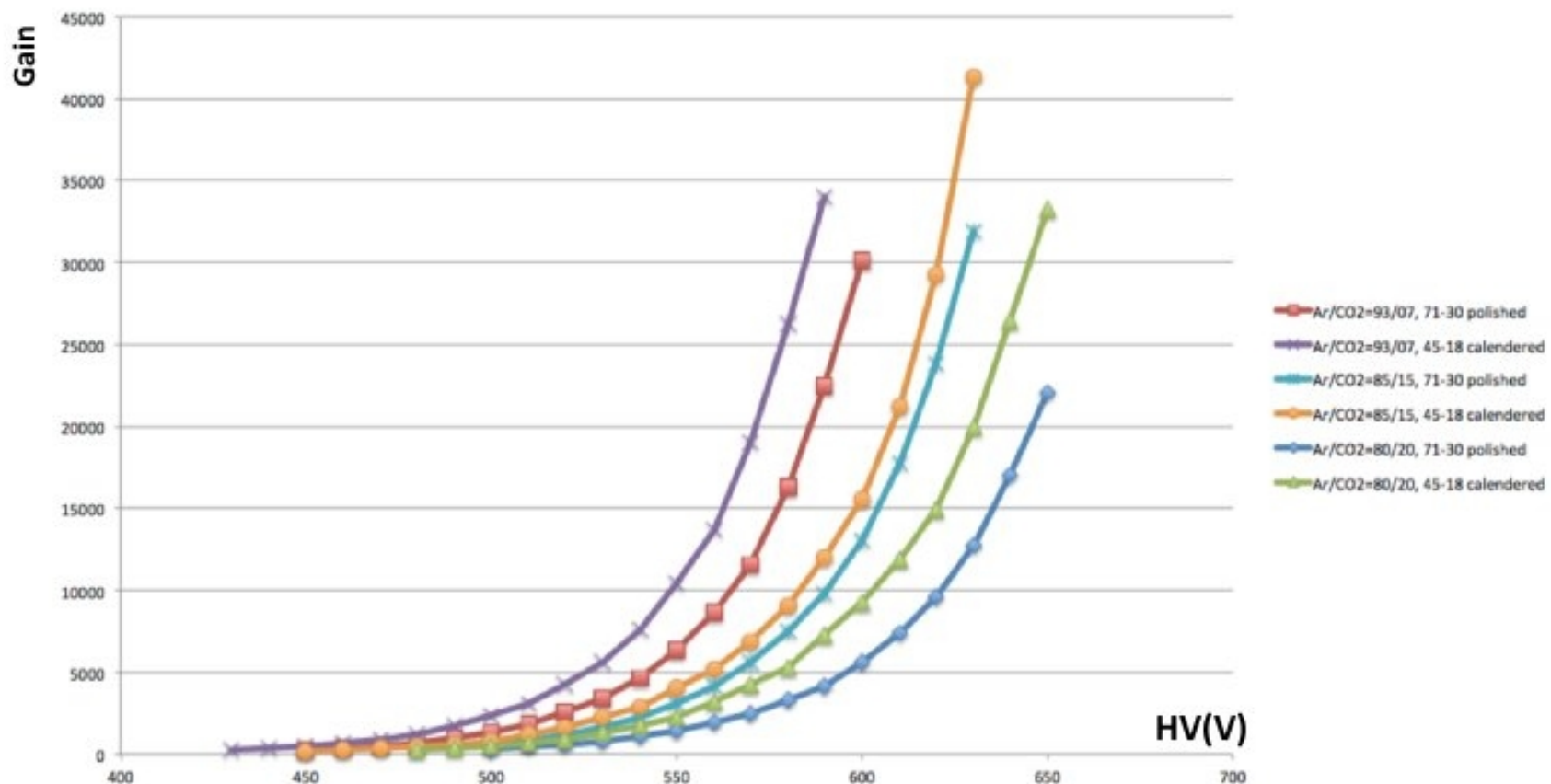
turn on curves not fully compatible with factor of 2 higher pulse height @ 18/45

- Efficiency: Cluster (min. 3 strips) within ± 5 mm from prediction
- $E_{drift} = 600 \text{ V cm}^{-1}$
- (30-71) μm seems to have steeper turn-on curve
- At plateau: insignificant difference between both meshes
- $\epsilon \geq 95 \% \quad U_A \geq 550 \text{ V}$

$U_{work} = 550 \text{ V ? for ExMe Chamber}$

Gas mixture comparison

- Mesh: 45/18 and 30/71 polished
 - Higher gain of 45/18 for all mixtures, difference seems not to be constant with CO₂ fraction



E-Field at Micromeshes

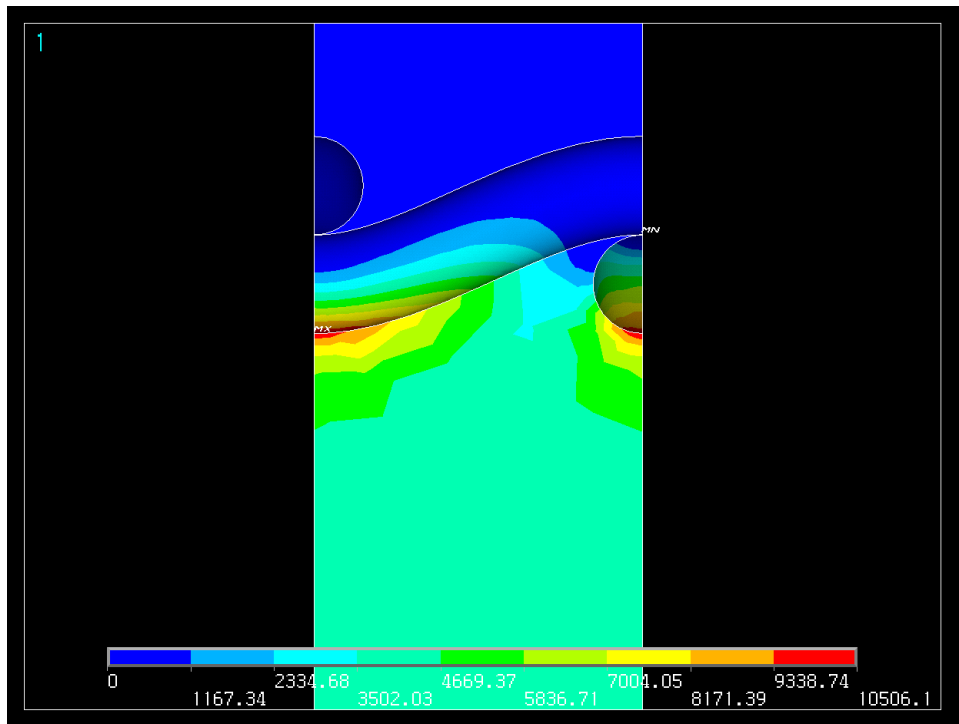
Anslys Simulation (M. Herrmann)

$U_{\text{anode}} = 540 \text{ V}$ $U_{\text{drift}} = -300 \text{ V}$

simulation of a calendared mesh

SM2

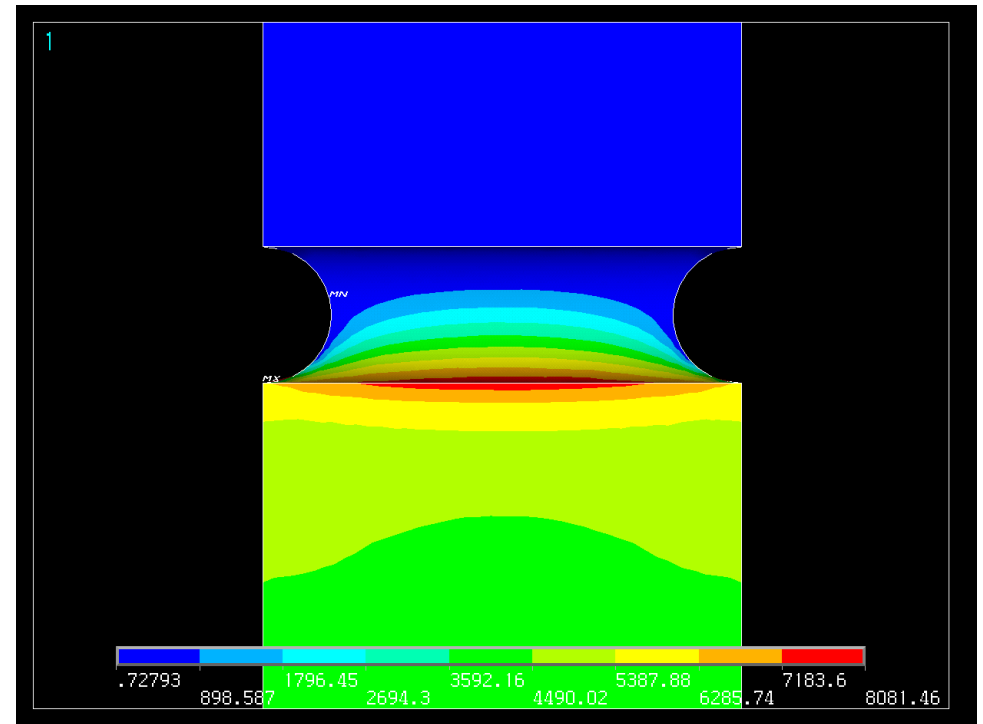
T-chamber



plain weave mesh 30-71
120 μm

$E_{\text{max}} = 105 \text{ kV / cm}$

$E = 44 \text{ kV / cm}$



flat mesh 18-45
120 μm

$E_{\text{max}} = 81 \text{ kV / cm}$

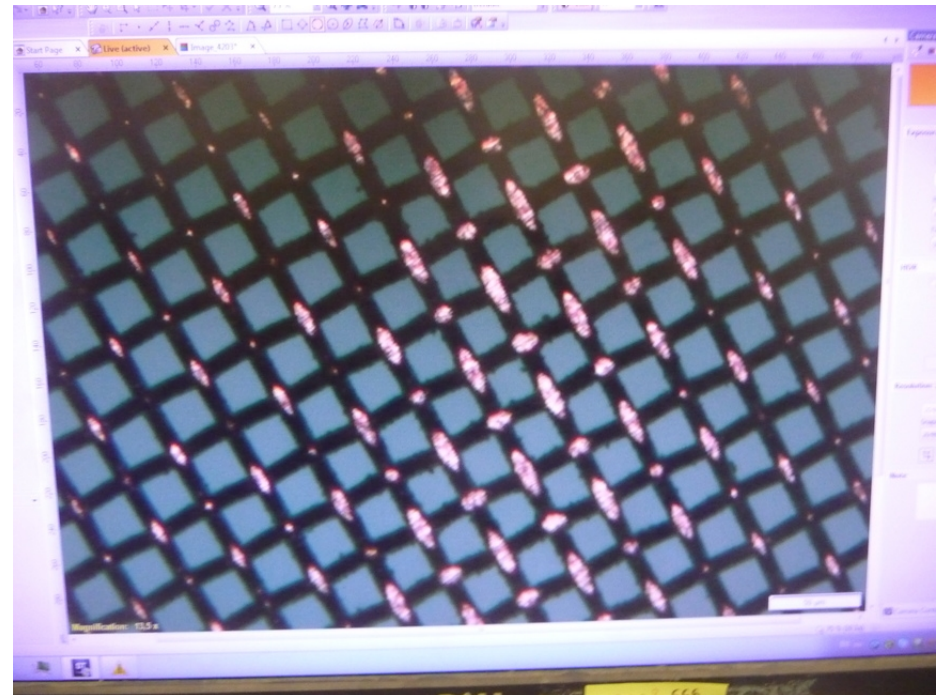
$E = 36 \text{ kV / cm}$

NB: the weakest point defines the break through voltage !
polishing of the mesh might be beneficial

SM2 M3 Doublet:

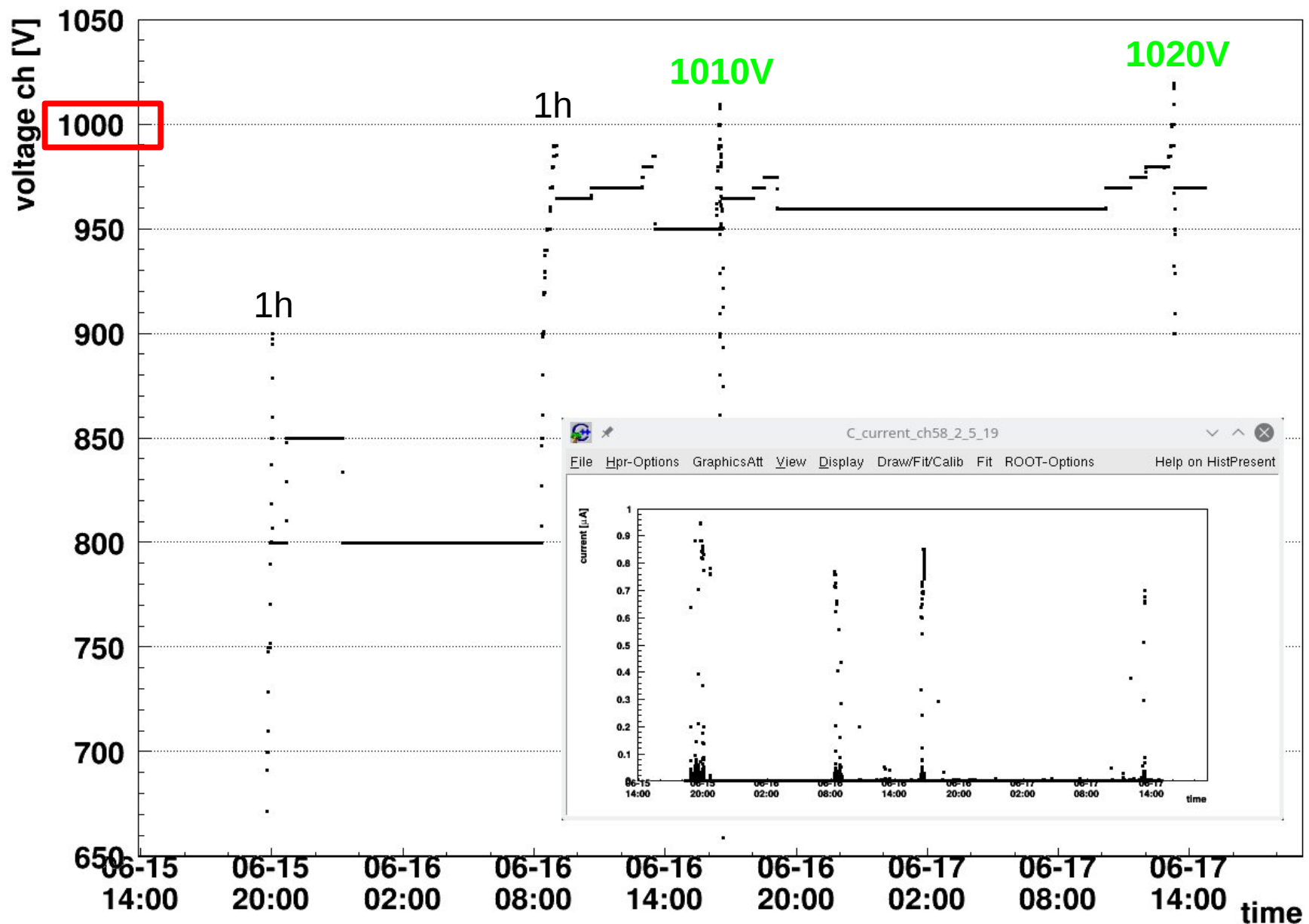
stereo4
+
2x polished drift
panel

assumption: polishing of the mesh
=>
less E_{field} exaltation



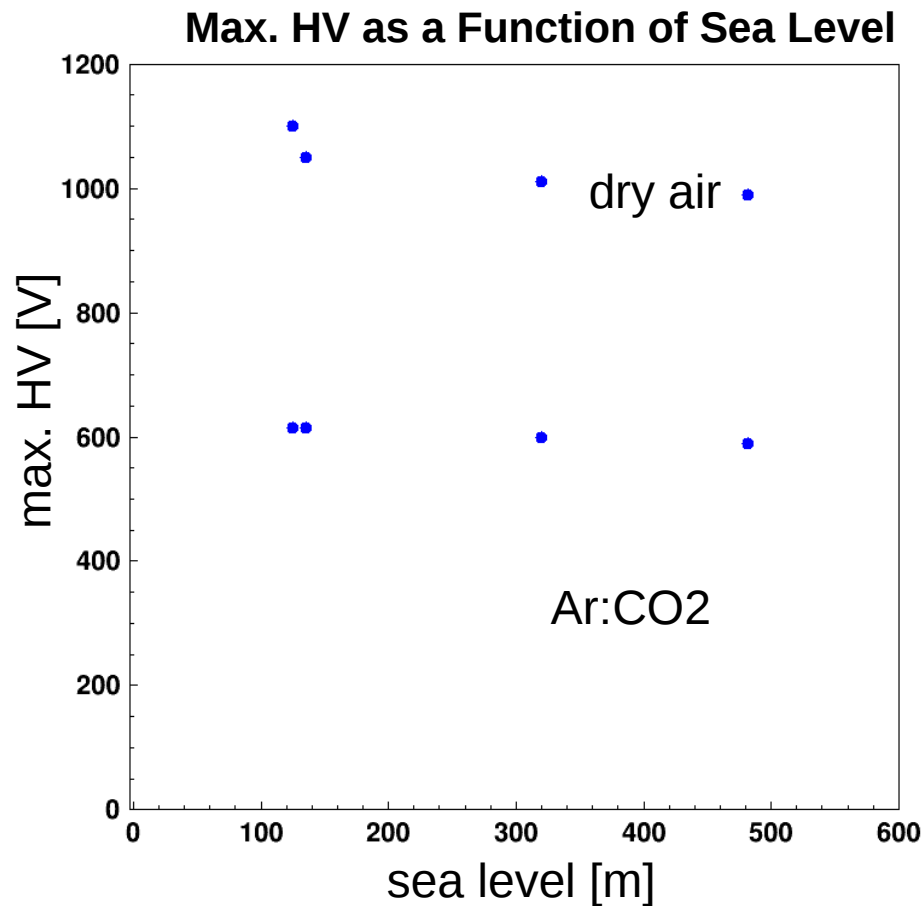
SM2 M3 Doublet: HV Scan Example HV Sector 2.5

HV Ramp-Up Started Immediately After Assembly
Together With Dry Air Flushing



quiet currents, higher values only during change of HV $U_{\max}=1000\text{V}$ 10/12 sectors

All 4 Production Sites Experience Similar Results



Dubna: 125 m

Saclay: 130 m

Frascati: 320 m

Garching: 482 m

$U_{\text{work}} = 570 \text{ V} \rightarrow 550 \text{ V}$ is under investigation

- polished meshes, calendared meshes I, D, Cern
- gas studies Cern, F, D, I
- VMM electronic + drifttime including analysis

Summary :

3 multiplets have been cleaned
cleaning works, 1x wet cleaning
but several reopenings still necessary for successful dry cleaning

excellent spatial resolution under cosmics
efficiency high, but not too high yet (missing strips, zebra ?)
similar HV behaviour for all 3 multiplets => systematic effect ? mesh ?
similar HV behaviour for the other multiplets from the other 3 sites

potential degradation of HV behaviour by time at a few HV sectors
narrow dynamic range between U_{\max} and U_{work}

the polishing of the mesh seems to have positive effects
but the results are not yet fully conclusive
a test in Italy shows no improvement using polishing
a comparison of calendared and uncalendared 30/71 mesh shows no effect using ExMe

test of M1 at SPS 120 GeV pion beams next week
VMM electronic
gas studies: Ar:CO₂ 93:7, Ar:CO₂ 85:15, Ar:CO₂:C₄H₁₀ 91:7:2, H₂O content

ExMe Chamber tests are ongoing: meshes, gas-mixtures

Bernhard Flierl
Maximilian Herrmann
Ralf Hertenberger
Felix Klitzner
Philipp Loesel
Ralph Mueller
Otmar Biebel

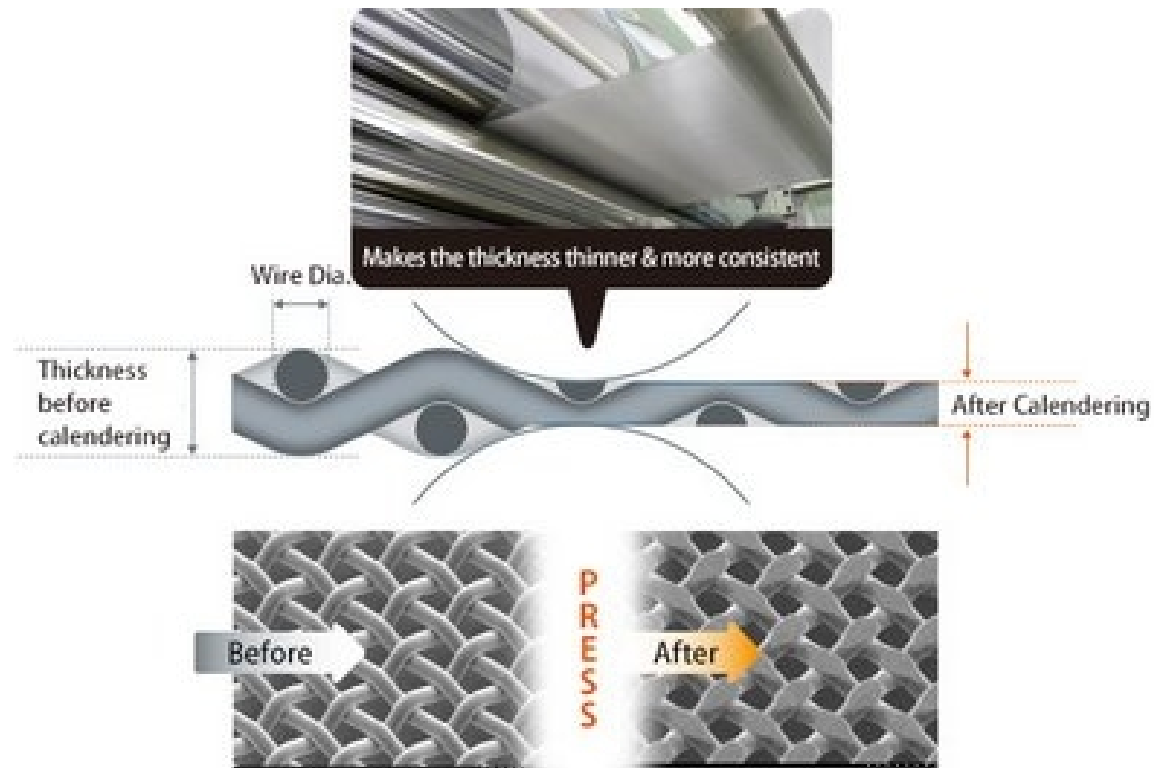
Paola Arrubarrena
Maximilian Feil
Stefanie Goetz
Laurent Jacques

Rui de Oliveira

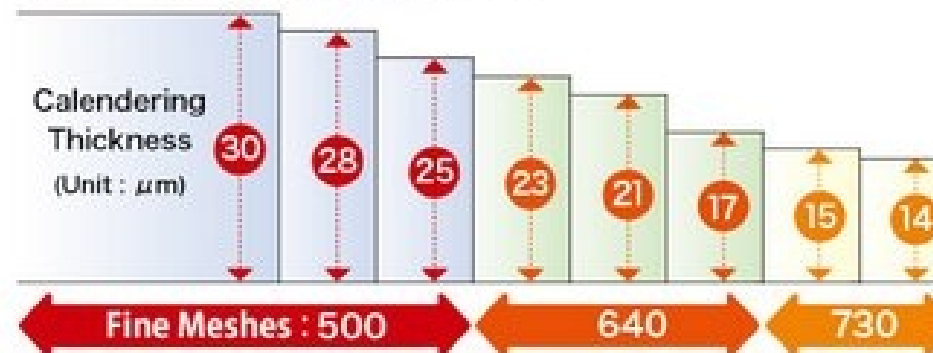
Givi Sekhniadze
Theo Alexopoulos
Paolo Iengo
Mariagrazia Alveggi
Mauro Iodice

Backup

Calendering of a Mesh



Fine Meshes and Calendering thickness



Thickness can be controlled with an accuracy level of 1.0 micron.

Gas mixture

- Results from old Micromegas prototype (bulk, non resistive)

